



Operating Manual

Transpector[®] CPX

Residual Gas Analyzer



INFICON

Two Technology Place

East Syracuse, NY 13057-9714

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1 Revision History

Date	Rev. Level	Description	Approval Service Engineer
07/10/2024	A	Initial release	Killian Hart

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These instructions do not account for every contingency that may arise in connection with the installation, operation or maintenance of this equipment. Should you require further assistance, please contact INFICON.

4 Safety

4.1 Definition of Cautions and Warnings

When using this manual, please pay attention to the notes, cautions and warnings found throughout. For the purposes of this manual they are defined as follows:



CAUTION

This is a Caution paragraph. It cautions against actions which may cause an instrument malfunction or the loss of data.



WARNING

This is a General Warning paragraph. It warns against actions which may cause bodily injury.



WARNING

This is an example of a Electrical Warning paragraph. It warns of the presence of electrical voltages which may cause bodily injury.

4.2 Personal Qualifications

All work described in this document may only be carried out by persons who have suitable technical training and the necessary experience.

4.3 General Safety Instructions



CAUTION

The product is not for use in a manner not specified by the manufacturer. If the product is used in a manner not specified by the manufacturer, the protection provided by the equipment may be impaired.



CAUTION

Only trained personnel may perform service actions on the product.

5 Getting Started

5.1 Purpose of Transpector CPX

Inspector[®] CPX samples a representative fraction of a process environment and directs the gas sample to a residual gas analyzer (RGA). Inspector CPX can detect levels of impurities in process gases at sub-parts-per-million (ppm) levels.

5.2 Description of Inspector CPX

Inspector CPX is composed of:

- FabGuard[®] Software: FabGuard software provides automatic or manual control and status information. It includes a full array of basic RGA features, including spectrum or selected peaks scanning, leak detection, and recipe generation.
- Quadrupole Sensor: the quadrupole sensor analyzes gases by: (1) ionizing the gas molecules, (2) separating the ions by their mass-to-charge ratio, and (3) measuring the quantity of ions at each mass. The sensor can indicate the partial pressure of the gases characteristic of processes occurring within a vacuum. It is used to investigate the nature of a process or to monitor process conditions.
- Electronics Module (Inspector): the electronics module controls the sensor, pumping system, valve actuation, heaters, and power to all elements of the system. The electronics module and quadrupole sensor are a matched set. The electronics module mounts on and is supported by the sensor.
- Pumping System: the pumping system provides process sampling from 1.2 atm to high vacuum.
- Inlet Valves and HexBlock[™] Inlet: the inlet valves and HexBlock inlet provide several sampling ranges, a calibration reference, and a process pressure gauge.

5.3 Physical Specifications

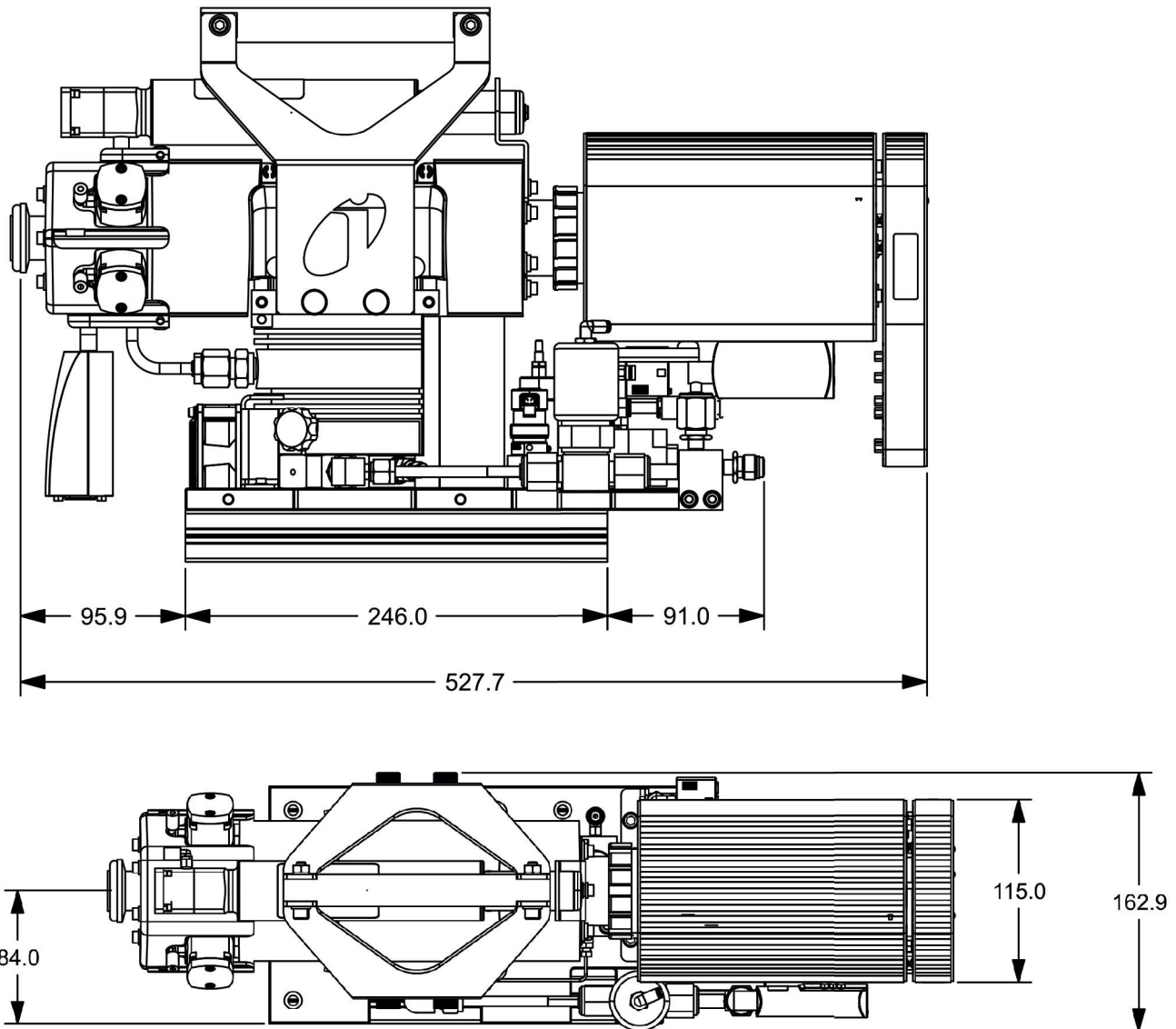
5.3.1 Physical Dimensions

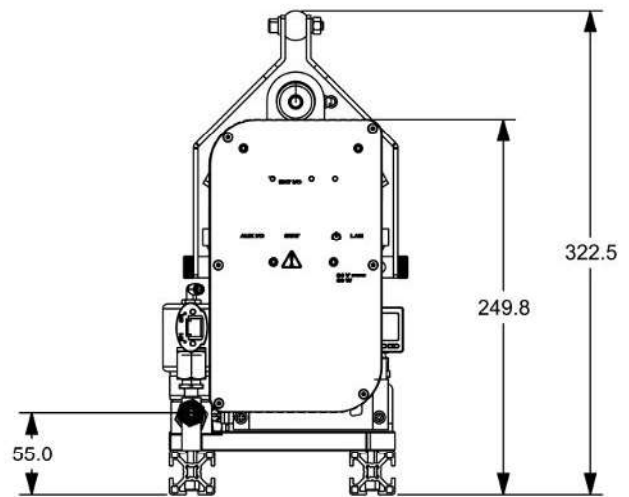
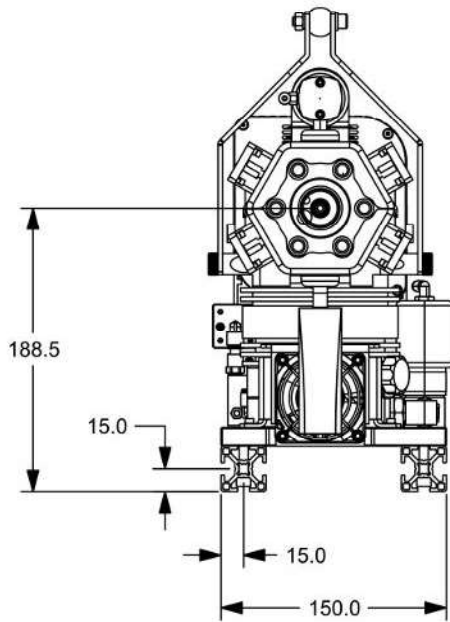
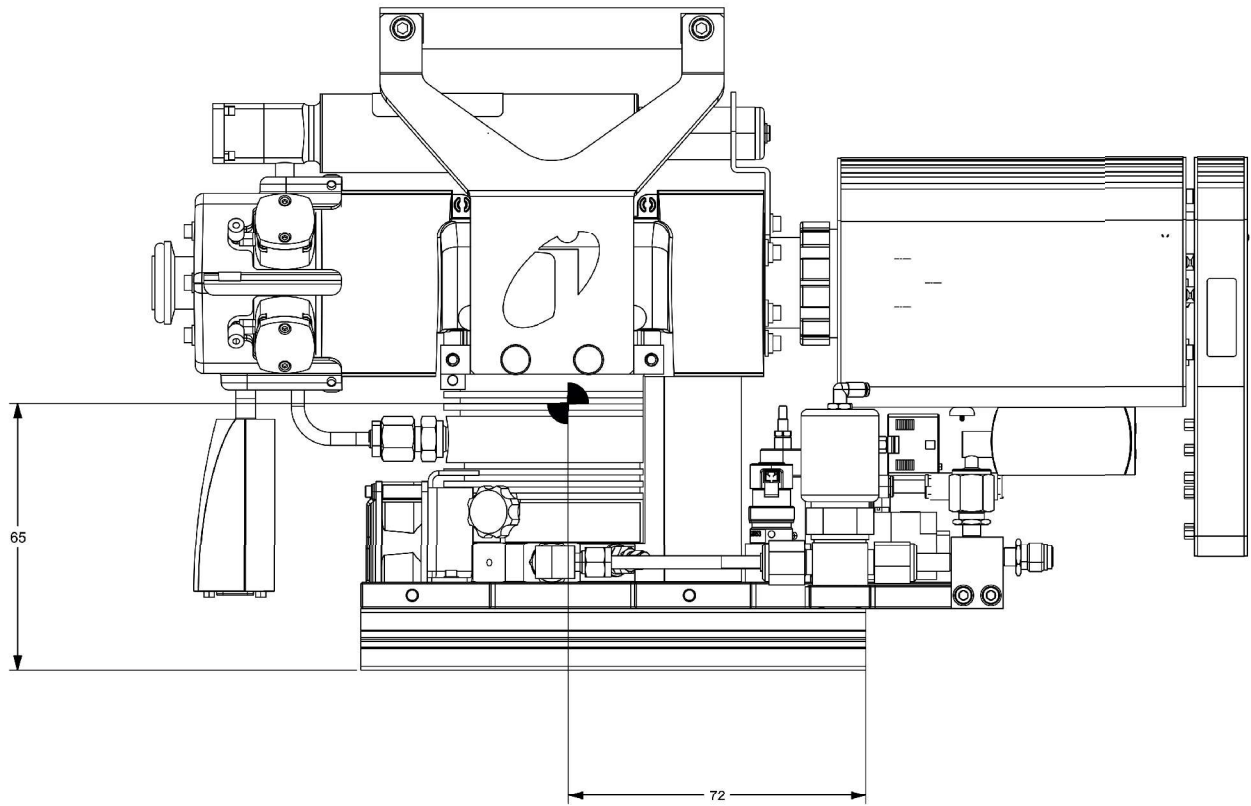
System dimensions: 527.7 mm × 162.9 mm × 322.5 mm (20.7 in. × 6.4 in. × 12.7 in.)

Foreline pump dimensions: 218 mm × 150 mm × 147 mm (8.6 in. × 5.9 in. × 5.8 in.)



Note that dimensions given use a KF25 in-line process connection; use of CF40 or KF40 may slightly change the length.





5.3.2 Weight

The approximate weight of Transpector CPX (without the foreline pump) is 14.1 kg (31 lb.). The weight includes all connecting cables.

5.3.3 Ventilation Requirements

If enclosing Transpector CPX, the enclosure must be large enough or ventilated to provide adequate cooling airflow to the fan on the Transpector CPX pumping system.



⚠ CAUTION

For adequate ventilation, maintain at least 25 mm (1 in.) clearance around the Transpector CPX electronics module, the Transpector CPX heaters, and the pumping system.

5.3.4 Electrical Power Requirements

The Transpector CPX system components that require AC power input are:

- Transpector CPX: use a universal input. Any voltage in the range specified in Acceptable Supply Voltage Range [▶ 17] is acceptable.
- Personal computer: use a universal input. Any voltage in the range specified in Acceptable Supply Voltage Range [▶ 17] is acceptable.

5.3.4.1 Required Supply Voltage

AC power input is required. The AC input voltage is supplied and regulated through the external power supply. Input voltage range: 90–264 V (47–63 Hz).



The power brick is certified/qualified for:

- DoE level VI efficiency
- Medical and ITE Certifications
- Class I

- Less than 0.5 W off-load power draw
- IEC60601-1-2 Ed4 and 60601-1-11
- Suitable for B and RF rated equipment
- Output cable and connector
- 2 m output cable with power D connector

5.3.4.1.1 Acceptable Supply Voltage Range

The AC voltage input must be within 90–264 V.

5.3.4.1.2 Required Frequency

The required frequency of the AC input power is 47–63 Hz.

5.3.4.1.3 Power Rating

The electronics module (electronics box and vacuum system interface) regulates all necessary currents for operation of all major components such as foreline pump, turbomolecular pump, and all cartridge heaters. The supplied voltage to those components is regulated at 24 V by the electronics box. Therefore, each component will require a different draw current at different states.

The rating of the current drawn by the Transpector CPX external power supply is 3 A maximum at 115 V (AC).

Power factor: Meets EN61000-3-2, >0.9 at 230 V (AC) full load.

5.3.4.1.4 Overvoltage Category

Overload and short-circuit protection: Hiccup mode (105–150%).

Overvoltage protection: Auto recovery.

5.3.4.1.5 Electrical Connections

The electrical connections are a 110 V (AC), three-pronged, grounded plug or a 230 V (AC), two-pronged plug with a ground contact. The plug can be U.S., U.K., European, or Israeli plug type.



CAUTION

Do not replace the power cord with an inadequately rated cord. The cord must be rated 10 A or higher.

5.4 Transpector CPX Data Sheet

5.4.1 Specifications

Mass range	1–100 amu	1–200 amu	1–300 amu
Peak width at 10% peak maximum	0.9 ± 0.05 amu		
Ion source type	Closed ion source		
Total pressure range ¹	5 × 10 ⁻⁷ to 1 × 10 ⁻³ Torr (6.6 × 10 ⁻⁷ to 1.3 × 10 ⁻³ mbar)		
Total pressure accuracy ²	±25% 1 × 10 ⁻⁶ to 1 × 10 ⁻³ Torr (1.3 × 10 ⁻⁶ to 1.3 × 10 ⁻³ mbar)		
Maximum ion source operating pressure ³	1 × 10 ⁻³ Torr (1.3 × 10 ⁻³ mbar)		
Nominal ion source operating pressure ⁴	2 × 10 ⁻⁴ Torr (2.6 × 10 ⁻⁴ mbar)		
System operating pressure (with orifices/capillary)	1 × 10 ⁻⁸ Torr (1.3 × 10 ⁻⁸ mbar) to 900 Torr (1200 mbar)		
Sensitivity at low emission, FC mode	>4.0 × 10 ⁻⁶ A/Torr (>3 × 10 ⁻⁶ A/mbar)	>2.0 × 10 ⁻⁶ A/Torr (>1.5 × 10 ⁻⁶ A/mbar)	>1.0 × 10 ⁻⁶ A/Torr (7.6 × 10 ⁻⁷ A/mbar)
Sensitivity at high emission, FC mode	>2.0 × 10 ⁻⁵ A/Torr (>1.5 × 10 ⁻⁵ A/mbar)	>1.0 × 10 ⁻⁵ A/Torr (>7.6 × 10 ⁻⁶ A/mbar)	>5.0 × 10 ⁻⁶ A/Torr (>3.8 × 10 ⁻⁶ A/mbar)
Maximum data rate (analog scans or selected peaks)	1.8 ms per point (555 data points per second)		
Abundance sensitivity ⁵	<5 ppm	<10 ppm	<100 ppm
Zero blast ⁶	<1 ppm	<15 ppm	<100 ppm
Detection limit ⁷	<10 ppb	<25 ppb	<50 ppb
Linearity ⁸	±20%		
Minimum background pressure	<1.0 × 10 ⁻⁸ Torr (<1.3 × 10 ⁻⁸ mbar)		
Maximum sensor and inlet operating temperature	Manifold: 120°C, inlet: 180°C		

1. The pressure reading at low emission using a total pressure lens.
2. The total pressure accuracy at low emission.
3. The maximum ion source operating pressure at low emission (the filament turn-off threshold).
4. 2 × 10⁻⁴ Torr (2.6 × 10⁻⁴ mbar) in the closed ion source produces 1 × 10⁻⁵ Torr (1.3 × 10⁻⁵ mbar) in the quadrupole region.

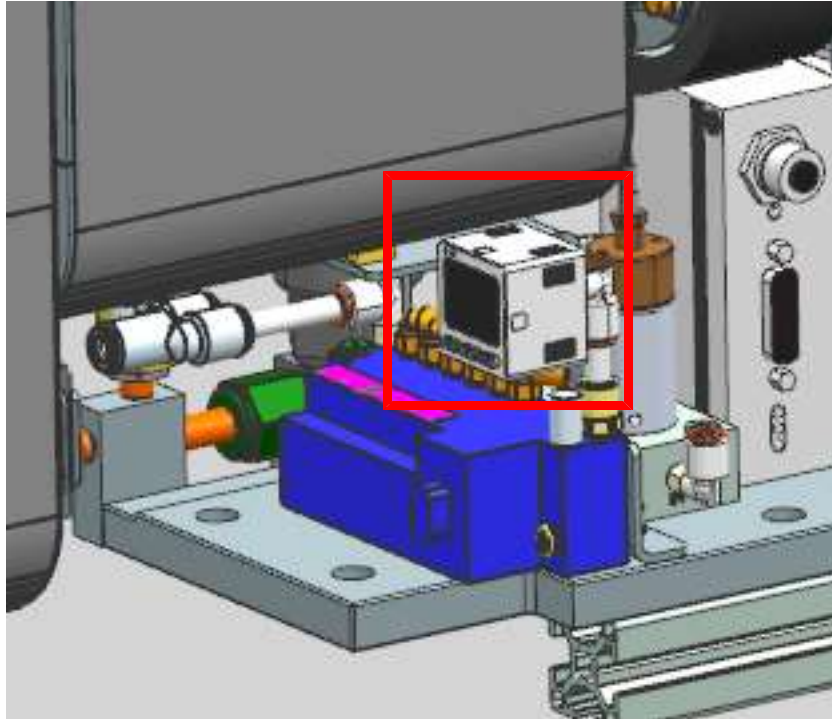
5. The mass 40 contribution onto 41 amu.
6. The zero blast contribution onto 2 amu.
7. The minimum detectable concentration with krypton in air at a two-second dwell time.
8. The specification is for 1 Torr (1.33 mbar) orifices and lower. This is the linearity specification at low emission at 0.1–2 times the nominal orifice pressure.

5.4.2 HexBlock Orifice Sampling Inlets

Inlet	Orifices
V1 (LP)	3 mTorr (4×10^{-3} mbar) (no orifice) 10 mTorr (1.3×10^{-2} mbar) 15 mTorr (2×10^{-2} mbar) 100 mTorr (1.3×10^{-1} mbar) 360 mTorr (4.8×10^{-1} mbar) 1 Torr (1.3 mbar) 3 Torr (4 mbar) 10 Torr (13 mbar)
V2 (HP)	3 mTorr (4×10^{-3} mbar) (no orifice) 10 mTorr (1.3×10^{-2} mbar) 15 mTorr (2×10^{-2} mbar) 100 mTorr (1.3×10^{-1} mbar) 360 mTorr (4.8×10^{-1} mbar) 1 Torr (1.3 mbar) (recommended bypass) 3 Torr (4 mbar) (recommended bypass) 10 Torr (13 mbar) (required bypass) 30 Torr (40 mbar) (required bypass) 1 Torr sniffer (1.3 mbar) (recommended bypass) 3 Torr sniffer (4 mbar) (recommended bypass) 7 Torr sniffer (9.3 mbar) (required bypass) 10 Torr sniffer (13 mbar) (required bypass) 30 Torr sniffer (40 mbar) (required bypass) 100 Torr sniffer (133 mbar) (required bypass)
V3 (H3)	1 mTorr (1.3×10^{-3} mbar) (no orifice)

5.5 Nitrogen Purge Gas (Corrosive System Only)

Nitrogen is recommended to use as the purge gas for corrosive pumping systems. The corrosive pumping system provides 8.5 ± 1 sccm of nitrogen purge gas to flow through its bearings to protect the bearings from corrosion and loss of lubricant by evaporation. For the corrosive pumping system, nitrogen gas is routed directly to the solenoid valve block and to the pressure regulator through a 6.35 mm (1/4 in.) tee. The supplied pressure is displayed on an LCD screen, attached to the solenoid. The location of the pressure switch is indicated in the illustration below.



The pressure gauge is rated for 58–120 psi (4–8.89 bar) [400–889 kPa]. The recommended supply pressure is 75–80 psi (gauge) (5.17–5.52 bar) [517–552 kPa].



⚠ CAUTION

The nitrogen pressure must be at least 58 psi (4 bar) [400 kPa] and must not exceed 120 psi (8.89 bar) [889 kPa].

5.6 Exhaust Gas

Exhausting gas from the turbomolecular pump is required for corrosive applications. If sampling toxic gas chemistries, it is essential that the exhaust port of the turbomolecular pump be connected to an abatement system at the factory. With noncorrosive applications, exhaust the turbomolecular pump in accordance with the facility's requirements. The dry foreline pump has a 6.35 mm (1/4 in.) VCR connection.

5.7 Pneumatic Pressure Requirements

5.7.1 Valves

The HexBlock and discrete inlet valves are pneumatic. The pilot valves are electro-pneumatic.

5.7.2 Pneumatic Pressure Range

Typically, dry nitrogen or dry air is used as pneumatic gas to actuate pneumatic valves. The pneumatic pressure range is 58–120 psi (gauge) (4–8.27 bar) [400–827 kPa]. The recommended setting is 75–80 psi (gauge) (5.17–5.52 bar) [517–552 kPa].

5.7.3 Moisture Content of Compressed Air Supply

Compressed air can be used as pneumatic gas if dry nitrogen is not available. The compressed air must be dry enough to avoid moisture condensation in lines, solenoids, or valve actuators.



CAUTION

Moisture condensation can cause corrosion.

5.7.4 Air Pressure Connections

The supplied pneumatic gas is delivered to the solenoid through a 6.35 mm (1/4 in.) polymer hose. The 6.35 mm (1/4 in.) connector is a friction-lock, right-angle fitting to adapt the supply hose to the solenoid base.

5.8 Vacuum Requirements

5.8.1 Required Vacuum

Transpector CPX requires a combination of foreline pump and turbomolecular pump to create vacuum conditions necessary for proper operation. The turbomolecular pump is always included with the system, where as the foreline pump is optional. Users may utilize the foreline pump of the tool on which the Transpector CPX is installed, if available.

In initial pumpdown, the foreline pump and turbomolecular pump start running simultaneously. The foreline pump evacuates the residual gas inside the foreline hose that connects to the system at the exhaust port. The Pirani gauge monitors the pressure at the exhaust port (also known as foreline pressure). Once the foreline pressure is below 12 Torr (16 mbar), the foreline isolation valve will open and the residual gas inside the Transpector CPX manifold will be pumped out by the turbomolecular pump and transferred through the foreline hose into the foreline pump. During initial pumpdown, also known as conditioning time, FabGuard software will lock the instrument to avoid any unwanted interruption.

If the foreline pump is not able to bring the foreline pressure from atmospheric pressure down below 12 Torr (16 mbar) within 2 minutes, the firmware will trigger a shutdown by closing the foreline isolation valve and shutting down the foreline pump and turbomolecular pump. If the foreline pump is the tool's foreline pump, the firmware will close the foreline isolation valve and shut down the turbomolecular pump only. When this happens, the user is required to execute initial pumpdown again through FabGuard software.

When the foreline isolation valve is open and the foreline pressure is under 12 Torr (16 mbar), the turbomolecular pump will accelerate to its maximum speed of 90,000 revolutions per minute (rpm). Once the turbomolecular pump reaches the maximum speed and emission is turned on, the initial pumpdown is completed, emission and electrometer will be turned on automatically, and then the system is ready for use.

When the foreline pressure is below 12 Torr (16 mbar) and the foreline isolation valve is open during initial pumpdown and during normal operation, if the exhausted gases flow back into the system and increase the foreline pressure up to 10 Torr or higher, the system allows 10 seconds for the turbomolecular pump and the foreline pump to bring the foreline pressure below 10 Torr. If the system fails to achieve under 10 Torr after 10 seconds, the firmware will trigger its safety interlock by closing the foreline isolation and shutting down the turbomecular pump and the foreline pump to protect the sensor from back-streaming gases.

5.8.2 Acceptable Range of Vacuum

The Transpector CPX manifold can achieve $<1 \times 10^{-8}$ Torr (1.3×10^{-8} mbar) of base pressure (when there is no sample flow) after bakeout and cool down. This level of vacuum requires a foreline pressure of <12 Torr (16 mbar).

5.9 Environmental Requirements

5.9.1 Use

The instrument is for indoor use only.

5.9.2 Altitude Range

The instrument can be used up to an altitude of 2000 m (6561 ft.). Contact INFICON for operation instructions at higher altitudes.

5.9.3 Maximum Humidity

The instrument can be used up to 80% relative humidity (no condensation).

5.9.4 Pollution Degree

The instrument can be used at a pollution degree of 2 (per EN61010-1:2010).

5.9.5 Maximum Operating Temperature

The maximum ambient operating temperature is 35°C (95°F).

5.9.6 Minimum Operating Temperature

The minimum operating temperature is 5°C (41°F).

5.9.7 Clean Room Requirements

Transpector CPX is clean room compatible.

5.9.8 Anti-Static Conditions

Transpector CPX passes standard EN 61326-1:2020.

5.10 Computer System Requirements

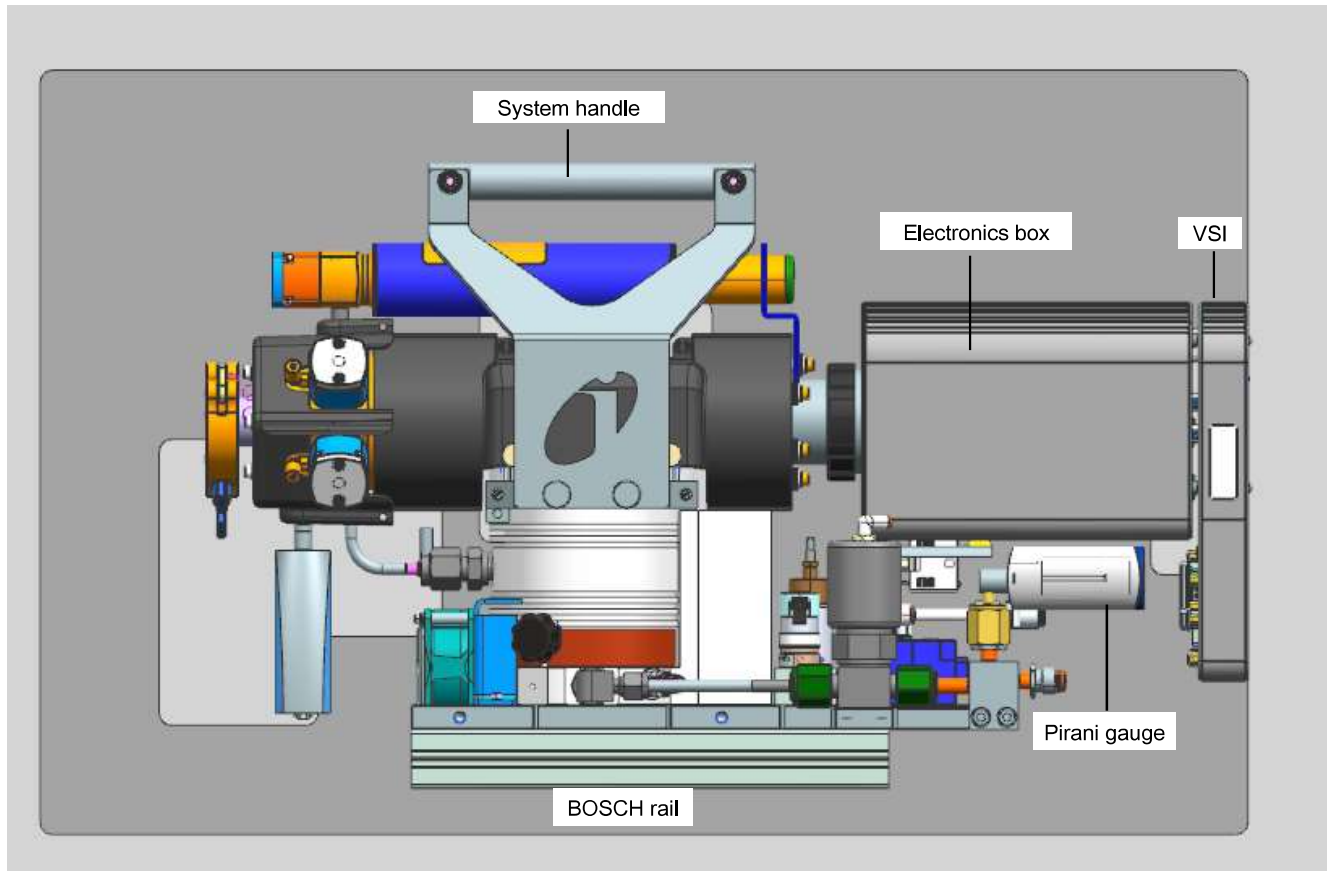
The minimum system requirements for FabGuard Explorer operating software are listed here:

Parameter	FabGuard Node Requirements
Processor	4.0+ GHz quad core
Memory	16+ GB recommended
Hard drive	Data 500 GB to 1 TB SSD
Resolution	1024 × 768 16-bit color or greater
Ethernet port	One free Ethernet port to allow connection to Transpector CPX
Operating system	Windows® 7 or 10

INFICON can supply a controller to run the software that operates Transpector CPX.

6 Installation

The Transpector CPX system is shipped with the electronics module attached to the sensor module as shown and sandwiched between two plastic panels. If the system includes the foreline hose and/or a diaphragm foreline pump, these will be packaged separately. All the connecting cables from the vacuum system interface (VSI) will be installed in the designated ports at the factory prior to shipping.



- 1 Install sniffer or capillary, if applicable.
- 2 Mount Transpector CPX to the process tool, if applicable.
- 3 Install the Transpector CPX foreline pump, if included.
- 4 Install pneumatic supply gas and purge gas, if applicable.
- 5 Install FabGuard software.
- 6 Establish communication between Transpector CPX and FabGuard.
- 7 Pump down Transpector CPX.



Lint-free gloves should be worn whenever installing or maintaining vacuum components to avoid impacting vacuum cleanliness.

6.1 Ambient Temperature Requirements

The Transpector CPX electronics module must be mounted in an area where the ambient temperature does not exceed 35°C (95°F) and there is ample air flow. The best performance is achieved when the electronics module is not exposed to wide temperature variations.

6.2 Sniffer or Capillary Installation

Install the sniffer or capillary into the Swagelok® fitting on the HexBlock using the 14.3 mm (9/16 in.) nut and vespel ferrule supplied with the sniffer.

6.3 Mount the Pumping System

Transpector CPX typically mounts directly to a process chamber via a CF or KF process connection at the end of the HexBlock inlet. Normally, there is no need to use an additional isolation valve between HexBlock and the process chamber. When all HexBlock valves are closed, HexBlock effectively acts as an isolation valve.

If an isolation valve is needed and Transpector CPX does not have a capacitance diaphragm gauge (CDG) interlock for the HexBlock inlet, it is essential to pump down the volume between HexBlock and the isolation valve from the process side before Transpector CPX is turned on. If this volume is not pumped down properly, filament failure can result.



CAUTION

If an isolation valve is used, ensure any trapped volumes are pumped out in order to avoid filament failure.

A support kit is supplied for Transpector CPX configurations with a standard process connection. The support kit, PN 922-209-G1, consists of two 1.22 m (4 ft.) support legs, two adjustable feet, and mounting hardware.

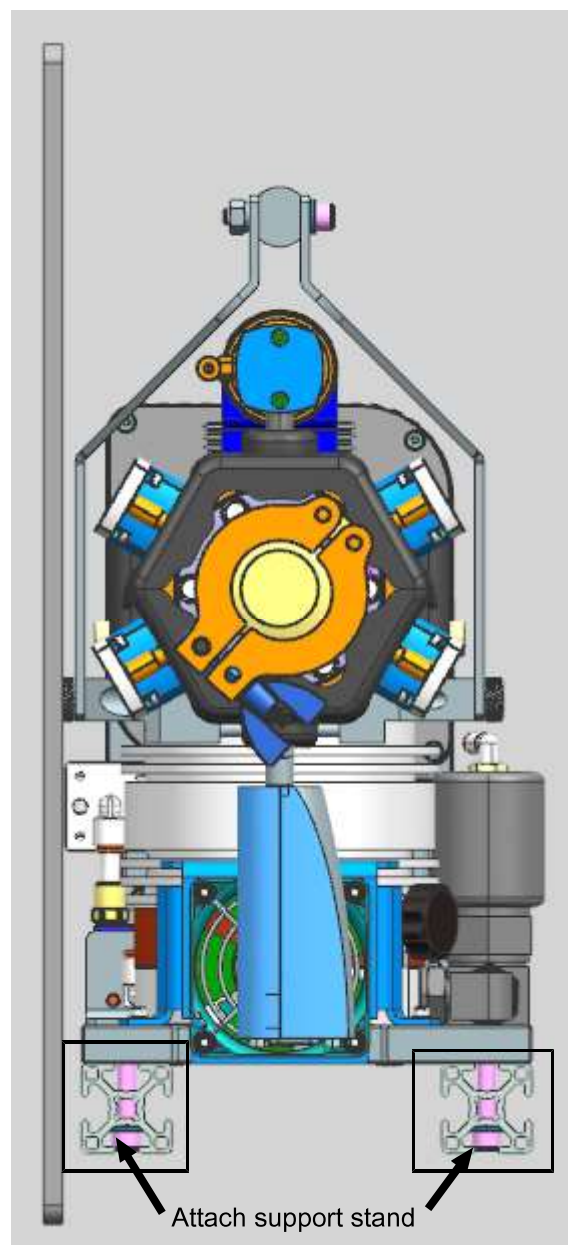


CAUTION

When installing Transpector CPX, make sure it is properly secured in case of a seismic event.

6.3.1 Install the Support Kit

- ✓ Two BOSCH® rails underneath the system base plate are designed to support installation. Support legs can be attached to these BOSCH rails with provided hardware.
- ✓ Measure the support leg to make sure that there is ample room for installation. The legs may be cut to size. One end of the support leg has a threaded hole for an adjustable foot. When cutting the leg, make sure that the threaded hole end is used for the support.
 - 1 Screw the adjustable foot fully into the bottom of the support leg.
 - 2 Install the right-angle bracket onto the support leg using the T-nut and bolts provided. Finger-tighten the bolt.



- 3 Install the second bolt and T-nut into the bracket, leaving it loose.
- 4 Slide the T-nut into the Transpector CPX mounting rail slot and adjust the position of the leg so that it is perpendicular to the floor with the adjustable foot about 12.7 mm (1/2 in.) from the floor.
- 5 Tighten all of the hardware.
- 6 Install the safety cap on the support leg.
- 7 Unscrew the adjustable foot until it supports Transpector CPX and relieves pressure from the flange.
- 8 Tighten the lock nut on the adjustable foot against the support leg.

6.4 Foreline Pump Installation

The 24 V (DC) dry foreline pump has the following connections:

- An electrical connection to the Transpector CPX vacuum system interface.
- A foreline hose connection to the foreline isolation valve/Pirani assembly connection.
- An exhaust port connection. This connection is required for corrosive or toxic gas sampling. Refer to the appropriate standards, such as SEMI S6-0707E, for exhaust gas guidelines.



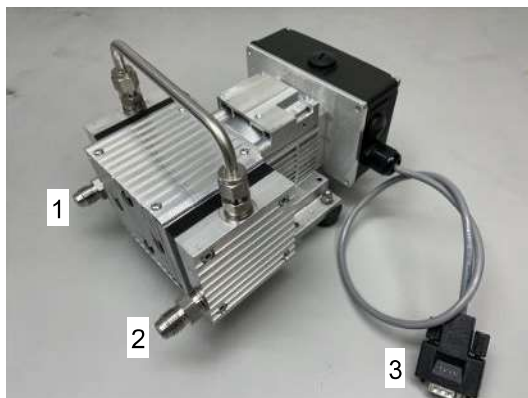
⚠ WARNING

Proper exhaust connections must be installed when sampling toxic, corrosive, or any hazardous gases to protect the environment from lethal levels of gas.



⚠ CAUTION

If a customer-supplied foreline pump is used, it must provide a continuous pressure below 12 Torr (16 mbar).



1	Exhaust port	2	Foreline connection	3	Foreline power cable
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6.5 Software Installation

Refer to the FabGuard Help website (<https://help.inficonims.com/>) for information regarding software installation.

7 Connecting the Instrument

Transpector CPX communicates via Ethernet. Devices on an Ethernet network have two identifying addresses: an IP address and a MAC address.

- IP addresses are assigned to identify individual devices on a network. Each device on an Ethernet network, including the host computer, must have a unique IP address. IP addresses can be reassigned to other devices on the network as long as each device has a unique IP address.
- MAC addresses are unique for each device. MAC addresses are never duplicated.

7.1 General Networking Information

7.1.1 IP Addresses

IP addresses can be either static or dynamic.

- Static (manual) IP addresses are set by the user and are changeable by the user. Static IP addresses are preferred.
- Dynamic (automatic) IP addresses are automatically set by a host or by a server on a network. Dynamic IP addresses can be set through dynamic host communication protocol (DHCP).



When using static IP addresses on a large network (for example, on a company network), a block of addresses should be reserved for static IP address use and prohibited from being assigned by the DHCP server (host). This will avoid duplicate IP address conflicts.



CAUTION

Use static IP addresses with Transpector CPX. Using DHCP, the host server may generate a new IP address if Transpector CPX is taken offline and then returned online or if there is an IP address conflict on the network.

If the Transpector CPX IP address is randomly changed during data acquisition, FabGuard will not reconnect to the new sensor IP address. This will result in a loss of communication and a loss of data.

Transpector CPX follows the IPv4 IP address convention. An example IP address is 192.168.1.100. Each of the four parts is referred to as an “octet.” The IP address consists of a network prefix and a host protocol.

7.1.2 Subnetworking

An IP network can be split into multiple subnets. Subnetting sets a region of the IP address as a network prefix for all IP addresses inside the subnet through a subnet mask. The subnet mask determines which octets of the IP address are used as the network prefix.

In order for two network devices to communicate, they must be on the same subnet, be connected to the same internet network and have the same network prefix.



If two devices have different network prefixes, the two devices are on different subnets.

	Example 1	Example 2	Example 3
IP address	192.168.1.104	192.168.1.105	192.168.1.150
Subnet mask	255.255.255.0	255.255.0.0	255.255.255.192
Network prefix	192.168.1.0	192.168.0.0	192.168.1.128
Host protocol	0.0.0.104	0.0.1.105	0.0.0.22

7.2 IP Address

The default Transpector CPX IP address is 192.168.1.100 with a subnet mask of 255.255.0.0.



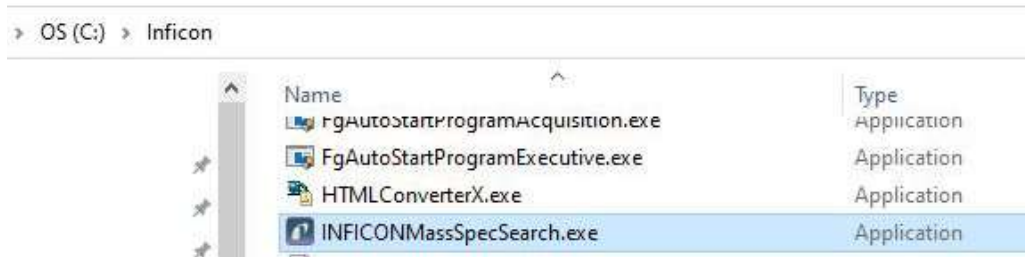
When connecting to an existing local network, there must be a static IP address for each Transpector CPX RGA. Contact the network administrator for IP address assignments.

Two methods of changing the Transpector CPX IP address are available:

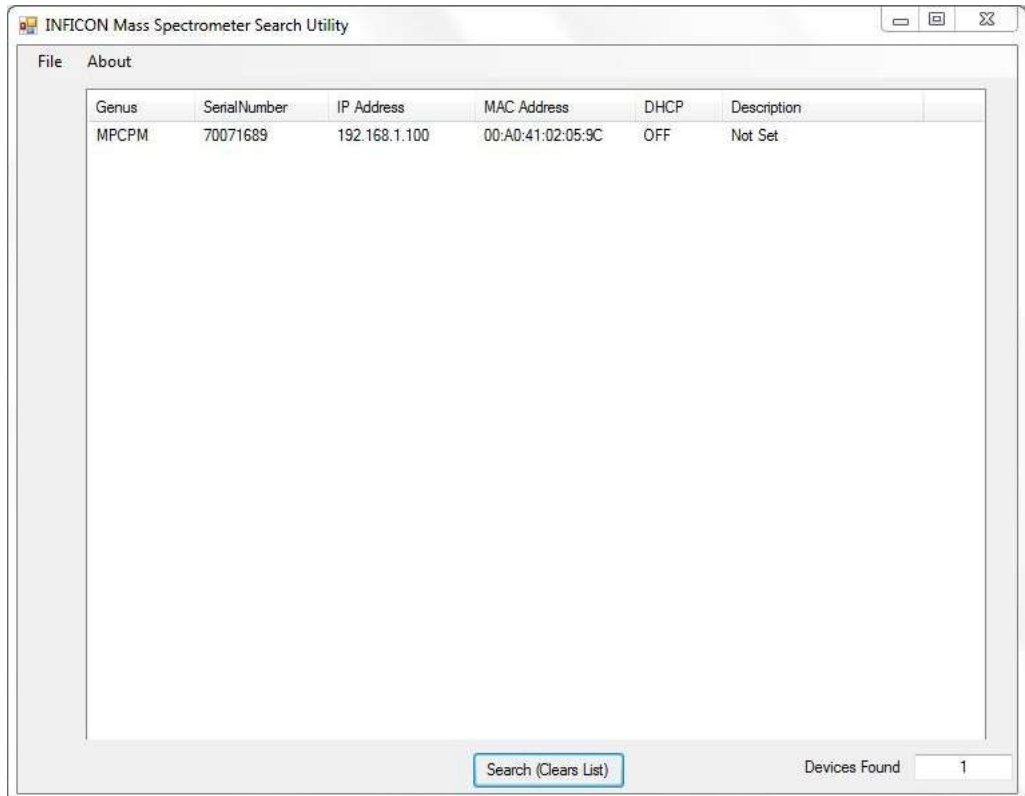
- INFICON Mass Spectrometer Search Utility
- Transpector CPX Web UI

7.2.1 Use the INFICON Mass Spectrometer Search Utility to Change the IP Address

The INFICON Mass Spectrometer Search Utility (IMSSU) is included with FabGuard Explorer software. Once the FabGuard Explorer software is installed onto the host computer, the user can find the **INFICONMassSpecSearch.exe** installer file in the directory **[C:\Inficon]**.



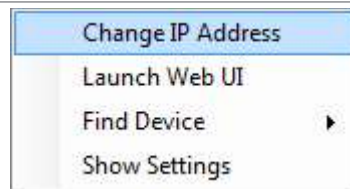
Right-click the file and select **Run as Administrator** to install the application software. The IMSSU opens as shown below.



The IMSSU detects every Transceptor CPX RGA installed on the network regardless of IP address. The IMSSU runs automatically and can be manually started or restarted by clicking **Search (Clears List)**. The display shows:

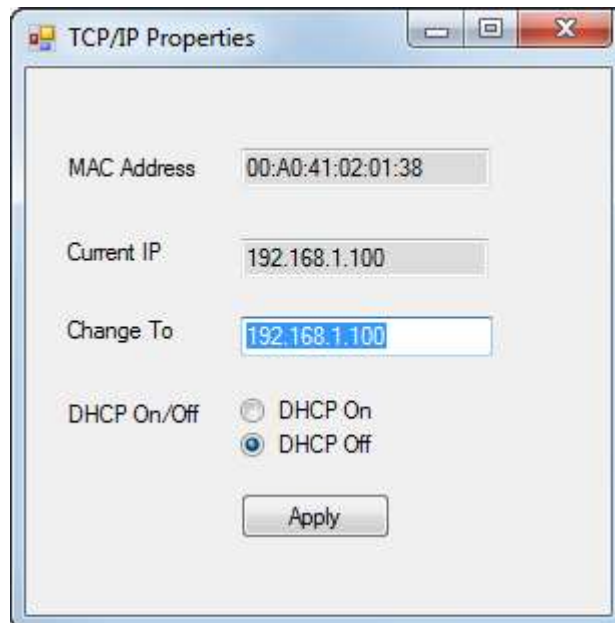
- **Genus** (MPCPM for Transceptor CPX sensors)
- **Serial Number**
- Current **IP Address**
- **MAC Address**
- **DHCP** status (On or Off)
- **Description** (user editable)

Right-click on a sensor to display the menu.



7.2.1.1 Change IP address

- 1 Right-click on the sensor and select **Change IP Address**. The **TCP/IP Properties** window displays. The **TCP/IP Properties** window displays the:
 - ⇒ Transpector CPX **MAC Address**
 - ⇒ Transpector CPX **IP address**
 - ⇒ **Change To** text box, to enter a new Transpector CPX IP address
 - ⇒ **DHCP On** or **DHCP Off** selection



CAUTION

Set DHCP Off so the IP address cannot be automatically reassigned.

- 2 Type the new IP address in the **Change To** text box.
- 3 Click **Apply**. Transpector CPX automatically reboots and returns online with the new IP address.
- 4 Launch the Web UI.

7.2.1.2 Launch Web UI

Transpector CPX Web UI can be launched from inside the IMSSU. Refer to the 074-581-P1 Transpector Web UI Operating Manual for instructions.

7.2.1.3 Find the Device

Find Device On flashes the power indicator on the device. The indicator flashes for up to 60 seconds and then illuminates.

Find Device Off selected within 60 seconds after selecting **Find Device On** stops the search.

7.2.1.4 Show Settings

Click **Show Settings** to display multiple settings useful for troubleshooting. The display shows:

- serial number
- gateway
- IP address
- DHCP status
- MAC address
- description
- subnet mask
- name
- description
- structure version
- box type
- port
- firmware version
- TCP/IP source

7.3 Connect the Instrument

Before connecting Transpector CPX, decide:

- Is Transpector CPX going to be on a private network (installed directly on either a computer or a router that is not hooked up to the internet) or an internal network where multiple computers are connected with access to the internet?
- Is more than one Transpector CPX sensor being installed at the same time?

7.3.1 Connect a Single Instrument

7.3.1.1 Single Sensor Direct Connection Installation

When installing a single Transpector CPX on a private network or connecting directly to a computer, changing the IP address of Transpector CPX is necessary only if the computer being used to connect to Transpector CPX has a different network prefix than Transpector CPX.

The default network prefix of Transpector is **192.168.x.x**. The IP address of the host computer used to control Transpector CPX must have a subnet mask of **255.255.0.0** and a network prefix of **192.168.x.x**.

If this is not the case, change the computer IP address to match the network prefix of Transpector CPX. For example, giving the computer an IP address of **192.168.1.101** allows Transpector CPX to communicate directly with the computer.

7.3.1.2 Install a Single Sensor on an Existing Local Network

When installing a single Transpector CPX on an existing local network, the default IP address of Transpector CPX may not be compatible with the network.

Transpector CPX can have either a static IP address (recommended) or a dynamic IP address set by DHCP (not recommended).

Contact the network administrator for information regarding valid IP addresses and ask the administrator to assign an IP address for Transpector CPX.

7.3.2 Install Multiple Sensors

Each Transpector CPX is shipped with an identical default IP address. When installing multiple Transpector CPX, the IP address of each Transpector CPX must be changed one at a time so that each Transpector CPX has a unique IP address.



CAUTION

Do not connect multiple Transpector CPX to a network without first changing the IP addresses. Otherwise, there will be IP address conflicts on the network.

7.3.2.1 Install Multiple Sensors Directly to a Host Computer

A private local network must be created when multiple Transpector CPX sensors are connected to a single host computer instead of an existing local area network.

Transpector CPX must be installed on either a router or Ethernet switch. The router or switch is connected to the host computer through the LAN port of the router/switch.

7.3.2.2 Install Multiple Sensors on an Existing Local Network

Use an Ethernet switch instead of a router when multiple Transpector CPX sensors are connected to an existing local network.



CAUTION

Routers can cause conflicts with local networks because the router will attempt to set IP addresses for all network connected devices.

Since Transpector CPX sensors are network connected devices, each sensor must have an IP address assigned to it by a network administrator. After changing each IP address manually, connect all of the sensors to the Ethernet switch and connect the switch to the local network.

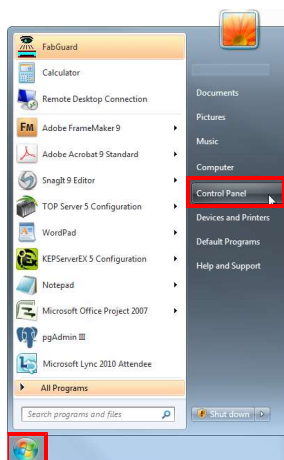
7.4 Change the Computer IP Address

An alternative to changing the Transpector CPX IP address is to change the host computer's IP address to allow communication between the host computer and Transpector CPX.

7.4.1 Windows 7

✓ Changing the IP address of the host computer requires administrator rights.

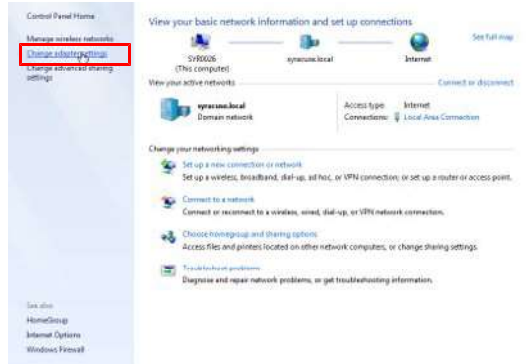
1 Click **Start**, then click **Control Panel**.



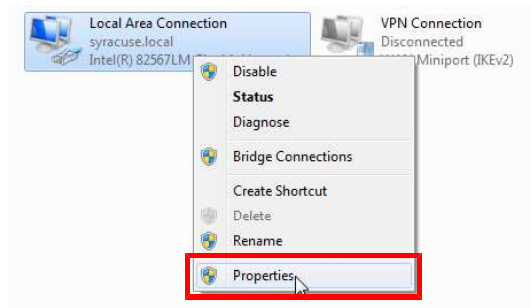
2 In the **Network and Internet** group, click **View network status and tasks**.



3 In the **Network Status and Tasks** window, click **Change adapter settings**.

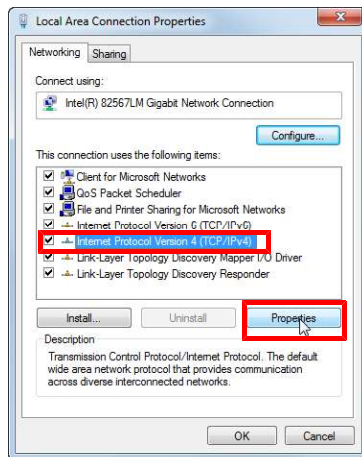


4 If the host computer is connected directly to Transpector CPX through the Ethernet port of the computer, right-click **Local Area Connection** and select **Properties**.

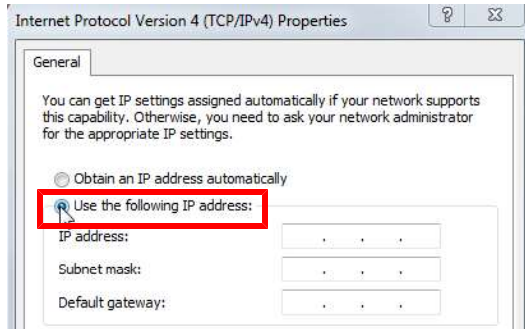


5 Click **Internet Protocol Version 4 (TCP/IPv4)**.

6 Click **Properties**.



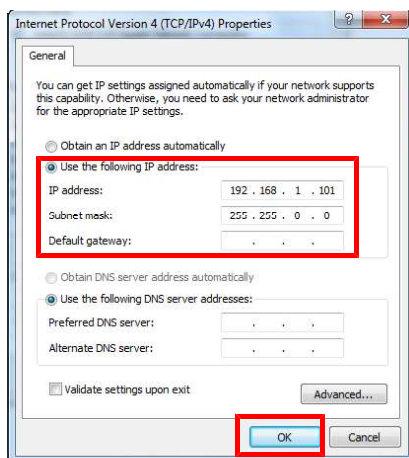
- 7** In the **Internet Protocol Version 4 (TCP/IPv4)** window, click **Use the following IP address**.



- 8** In the **IP address** field, type **192.168.1.XXX**. The last octet can be any number as long as it is unique to the network and is not the same as the Transpector CPX IP address.

- 9** In the **Subnet mask** field, type **255.255.0.0**.

- 10** Click **OK**.



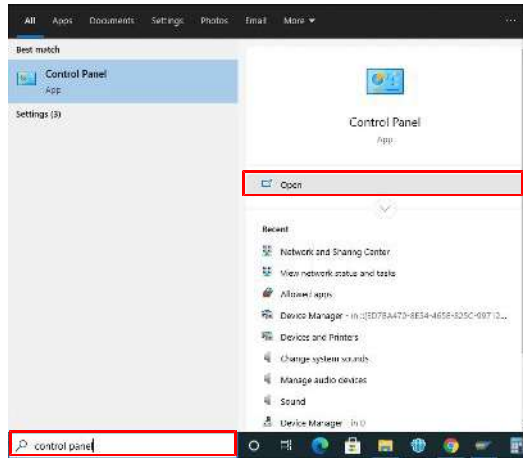
⇒ The IP address is now set to the manual IP address chosen in step 7.

- 11** Exit from all of the windows.
- 12** Connect to Transpector CPX.

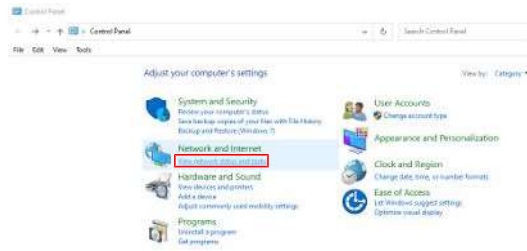
To change the IP address back to the default settings, follow steps 1 through 6 and reset the properties to their original settings.

7.4.2 Windows 10

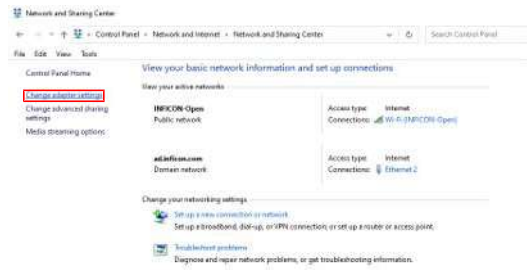
- ✓ Changing the IP address of the host computer requires administrator rights.
- 1** Search for **Control Panel**, then click **Open**



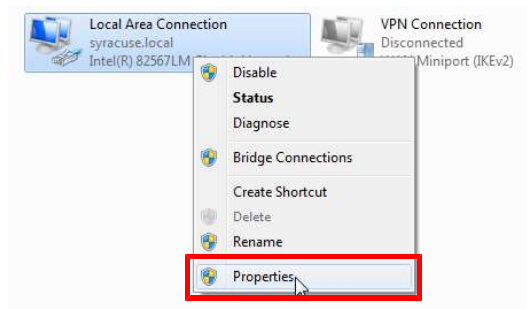
2 In the **Network and Internet** group, click **View network status and tasks**.



3 In the **Network and Sharing Center** window, click **Change adapter settings**.

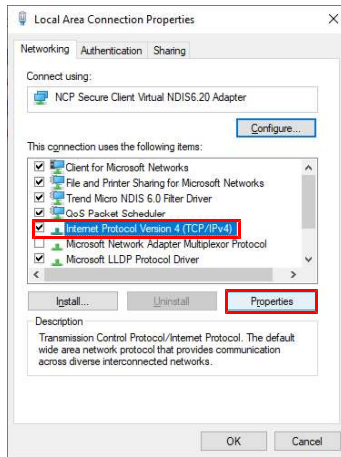


4 If the host computer is connected directly to Transceptor CPX through the Ethernet port of the computer, right-click **Local Area Connection** and select **Properties**.

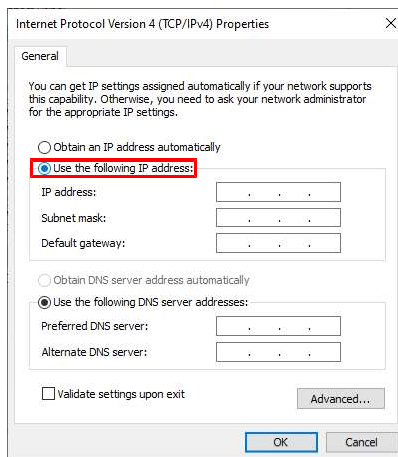


5 Click **Internet Protocol Version 4 (TCP/IPv4)**.

6 Click **Properties**.



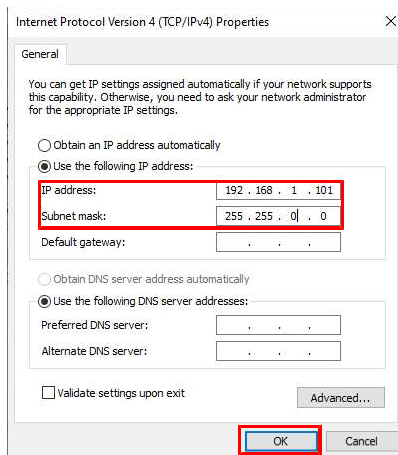
- 7** In the **Internet Protocol Version 4 (TCP/IPv4)** window, click **Use the following IP address**.



- 8** In the **IP address** field, type **192.168.1.XXX**. The last octet can be any number as long as it is unique to the network and is not the same as the Transceptor CPX IP address.

- 9** In the **Subnet mask** field, type **255.255.0.0**.

- 10** Click **OK**.



⇒ The IP address is now set to the manual IP address chosen in step 7.

11 Exit from all of the windows.

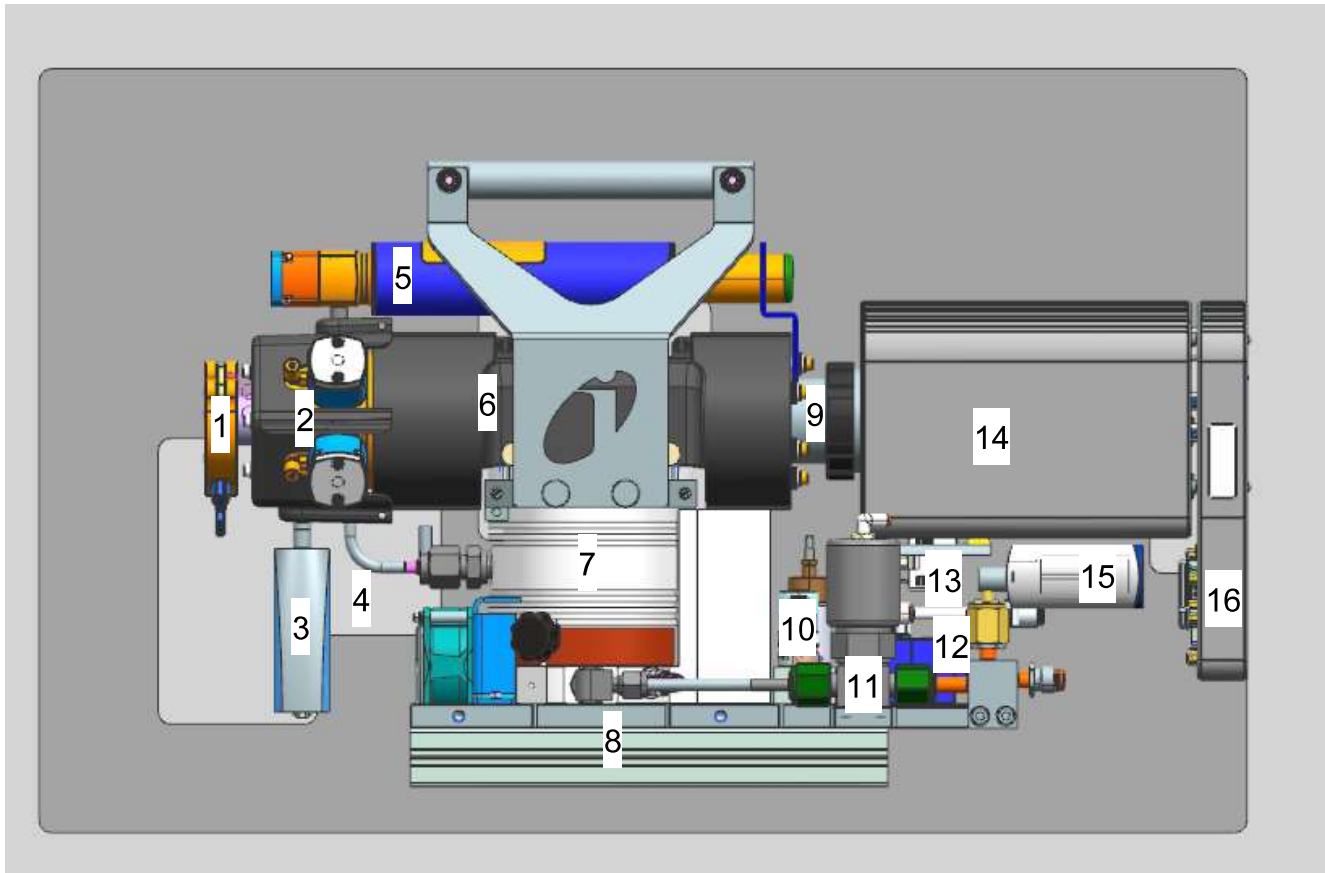
12 Connect to Transpector CPX.

To change the IP address back to the default settings, follow steps 1–6 and reset the properties to their original settings.

8 How the System Works

8.1 Components

An example of a fully configured Transpector CPX corrosive pumping system is shown below.



1	Process connection (CF40, KF40, or KF25)	2	HexBlock inlet	3	Process pressure gauge	4	Bypass connection for high-pressure applications
5	Calibration reference	6	Sensor manifold and heater	7	Turbomolecular pump	8	Base plate and rails
9	Transpector CPX sensor (inside the manifold)	10	Nitrogen regulator (for nitrogen purge and valve operation)	11	Foreline isolation valve	12	Valve solenoids
13	Pressure switch	14	Electronics module	15	Foreline Pirani gauge	16	VSI (vacuum system interface)

8.2 Theory of Operation

Many gas analysis applications involve pressures too high for direct exposure to the quadrupole sensor. In that scenario, a pressure reduction system is required to reduce the inlet pressure and maintain the pressure at the quadrupole sensor at an operational level. With a pressure reduction system, a quadrupole sensor may be used for high-pressure applications such as sputtering, chemical vapor deposition (CVD), etch, vacuum furnace analysis, and laser gas analysis.

The Transpector CPX pressure reduction system is an orifice or a combination of an orifice and a capillary or sniffer to reduce the partial pressure of the gas mixture at the process side, typically by a fixed proportion, with minimum mass discrimination. An orifice, a small disk with a defined radius hole, acts as a conductance limitation. When both the volume and the high vacuum pump speed are constant, the orifice hole size determines the magnitude of the pressure drop from the process pressure to the pressure at the sensor for proper operation. Orifices are available in various sizes to cover various pressure ranges.



⚠ CAUTION

FabGuard displays the total pressure inside the closed ion source.

Optimum performance is obtained when the total pressure display reads approximately 2×10^{-4} Torr (2.6×10^{-4} mbar) measured in low-emission mode (40 eV, 200 μ A) and in high-emission mode (70 eV, 2000 μ A).

8.3 Instrument Overview

8.3.1 Input/Output (Auxiliary I/O)

This section describes the available input and output (I/O) for Transpector CPX. Transpector CPX has two digital inputs, referred to as Remote Logic inputs, which default as emission control, two digital relay outputs (one of which reflects emission status by default), and two analog outputs. No analog input is available for Transpector CPX.

8.3.1.1 Auxiliary I/O Connector

User I/O is provided through a DA15 female connector, labeled "USER I/O" on the VSI module.

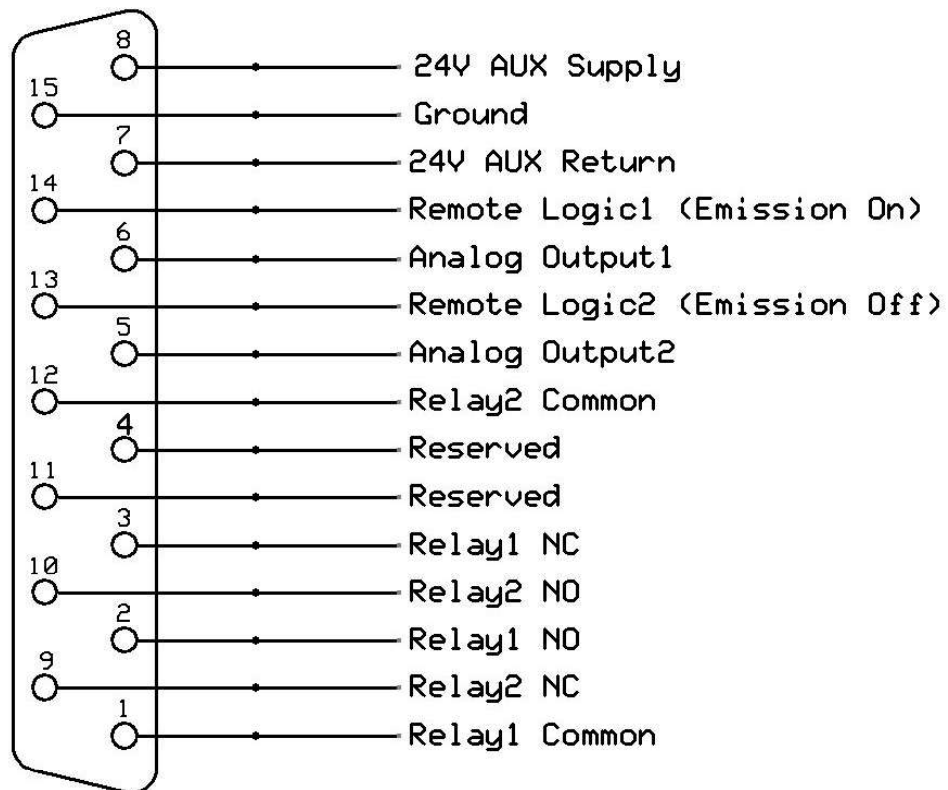
A mating DA15 male connector is supplied in the ship kit for connecting to the Transpector CPX auxiliary I/O connections.

8.3.1.2 Two Digital Inputs (Remote Logic)

Remote Logic 1 and 2 are by default set to remotely control the emission status. Remote Logic 1 turns on emission when transitioning from high to low. Remote Logic 2 acts as an emission interlock when in the low state, and will turn emission off when it enters the low state, if emission was on.

8.3.1.3 Two Relays

Two relays are available from AUX I/O. These relays may be used as digital outputs.



Relay 1	The relay is open = pin 2 and pin 1 are connected.
Relay 1	The relay is closed = pin 3 and pin 1 are connected
Contact rating	24 V (DC) at 0.5 A
Relay 2	The relay is open = pin 10 and pin 1 are connected
Relay 2	The relay is closed = pin 9 and pin 1 are connected
Contact rating	24 V (DC) at 0.5 A

8.3.1.4 Two Analog Outputs

Two analog outputs are available. The available analog output voltage range is from 0 to 10 V and can be configured through control software.

Analog output 1	Pin 6 and pin 15
Analog output 2	Pin 5 and pin 15

8.3.2 Ultrahigh Vacuum System

The vacuum system provides low pressure to:

- establish a sample flow from the process by pressure difference
- provide low pressure for optimum operation of the sensor

A dry pumping system comprised of a turbomolecular pump and a foreline pump is used to minimize hydrocarbons in the residual gas background. The turbomolecular pump provides a high compression ratio between the high vacuum side and the foreline pump side for all gases, including hydrogen. Hydrogen is the major residual gas component in ultrahigh vacuum. The high compression ratio for hydrogen is important for producing a low base pressure.

8.3.2.1 Foreline Subsystem

The foreline subsystem components include a flexible foreline hose of various lengths (≤ 10 m [≤ 32 ft.]), a foreline Pirani gauge, and a diaphragm foreline pump.

The foreline pump produces base pressures (when there is no gas flow) of 2 Torr (2.7 mbar), significantly less than the 12 Torr (16 mbar) needed for turbomolecular pump operation. The 2 Torr (2.7 mbar) operating pressure for the foreline is in the viscous gas flow regime such that the foreline does not require a large diameter. The inside diameter of the foreline is 6 mm (1/4 in.) which produces a 2 Torr (2.7 mbar) pressure drop across a 10 m (32 ft.) length of foreline at 20 sccm of gas flow. The foreline Pirani gauge can be used to troubleshoot pumping system problems and to verify that the turbo pump is being backed properly.

8.3.3 Heater(s) Subsystem

The heaters are zone-based cartridges with maximum temperature dependent upon the system configuration. The zones are divided into the Inlet Zone, the Manifold Zone, and the Auxiliary Zone. Plastic heater covers lined with insulation and an IR reflective material provide insulation.

The Transpector CPX VSI supplies power to the heaters.

Heater temperatures are defined in "Sensor Hardware Configuration" within FabGuard, and each zone can be controlled interdependently. Zone states can be controlled manually or via recipe within FabGuard.



WARNING

During or immediately after bakeout, the heater cover and metal surfaces in the vicinity of the heater cover are hot.

These surfaces exceed 100°C (212°F) at the maximum ambient operating temperature [35°C (95°F)] and can cause burns if touched.

8.3.4 Solenoid Valves

The solenoid-controlled valves are a group of valves joined together as one manifold assembly which is mounted to a bracket on the base plate.

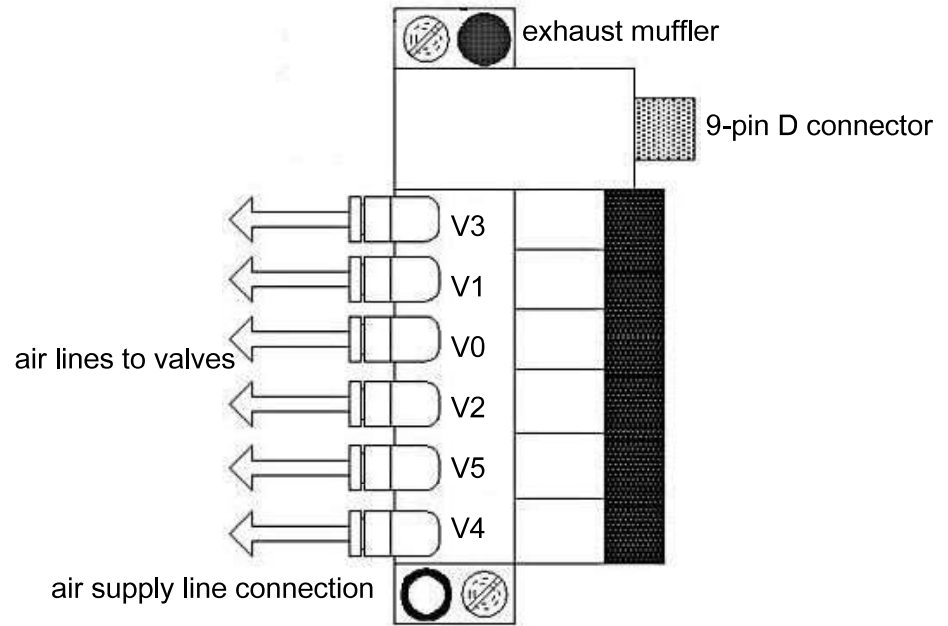
When solenoid valves are activated, compressed gas from the input gas supply [58–120 psi (4–8.27 bar) (400–690 kPa)] opens the appropriate valve. The recommended setting is 75–80 psi (5.17–5.52 bar) (517–552 kPa). All valves are electropneumatically operated. There are six solenoid valves on the valve block:

V0	V0 is the foreline isolation valve. The valve is automatically opened and closed by the start/stop of the pumping system.
V1	V1 is the low-pressure orifice valve for the HexBlock or the capillary sampling option. The valve is configured depending on the application. This valve is typically used for background monitoring.
V2	V2 is the high-pressure orifice valve for the HexBlock or the capillary sampling option. The valve is typically used for process pressure sampling. This valve is user-configured depending on the application.
V3	V3 is a high conductance valve [1 mTorr (1.3 mbar) maximum nominal pressure].
V4	V4 is a bypass valve. It is used in conjunction with the high-pressure bypass option for high pressure orifices or a sniffer or capillary sampling option.
V5	V5 is the calibration reference.

For more details about the function of each valve, see HexBlock Inlet [▶ 61].



Each solenoid has a red indicator that illuminates when the solenoid is activated.



8.3.5 Sensor and Electronics Module Subsystem

The sensor is a quadrupole partial pressure analyzer that analyzes gases by:

1. ionizing gas species
2. separating the ions by mass
3. measuring the quantity of ions at each mass

The masses, unique for each substance, allow the identification of the gas molecules from which the ions were created. The magnitudes of these signals are used to determine the partial pressures (amounts) of the respective gases.

The Transpector CPX electronics module mounts to the sensor and provides all of the requirements for operating the sensor, making the appropriate ion current measurements, communicating to a computer, and sending the resulting output to the computer.

The Transpector CPX VSI module contains all the cable connections to the various components of the Transpector CPX pumping system, including turbomolecular pump, gauges, and solenoid valves.

8.4 Application

The pumping and pressure reduction system reduces the pressure of process gas to allow proper operation at the ion source region. The pressure of 2×10^{-4} Torr (2.7×10^{-4} mbar) at the ion source region is considered optimal for partial pressure measurements for the closed ion source (CIS). The general formula to calculate the flow rate of gas that produces the optimal pressure is described as below:

$$Q = P_{\text{CIS}} S_{\text{CIS}}$$

P_{CIS} = the pressure at the CIS within the CPM manifold region

S_{CIS} = the pumping speed of the CIS

Q = throughput of the CIS (in Torr·L/s)

This flow rate produced by process gas flowing through the process gas orifice is:

$$Q = (P_{\text{Process}} - P_{\text{CIS}}) \times C_{\text{Process Orifice}}$$

where the conductance $C_{\text{Process Orifice}}$ determines the orifice diameters needed to produce this flow for each process pressure.

A selection of orifice diameters are available for reducing pressure for a multidecade range of (maximum) process pressures ranging from 0.001 to 100 Torr (1.3×10^{-3} to 133 mbar). For example, a 10 Torr (13 mbar) orifice has a 20 μm diameter hole to produce approximately 2×10^{-4} Torr (2.7×10^{-4} mbar) at the CIS when the process has 10 Torr (13 mbar) of nitrogen. Since process pressures can vary within the operating range of the process, different pressure reductions may be needed. The Transpector CPX system has a variety of inlet orifices that allow pressure range sampling which typically covers measurement of the base pressure of the process chamber (for leak detection and base vacuum analysis), with a high conductance port and two orifices for process pressures.

8.5 Sample Inlet Systems and Examples of Use

8.5.1 Inlet System

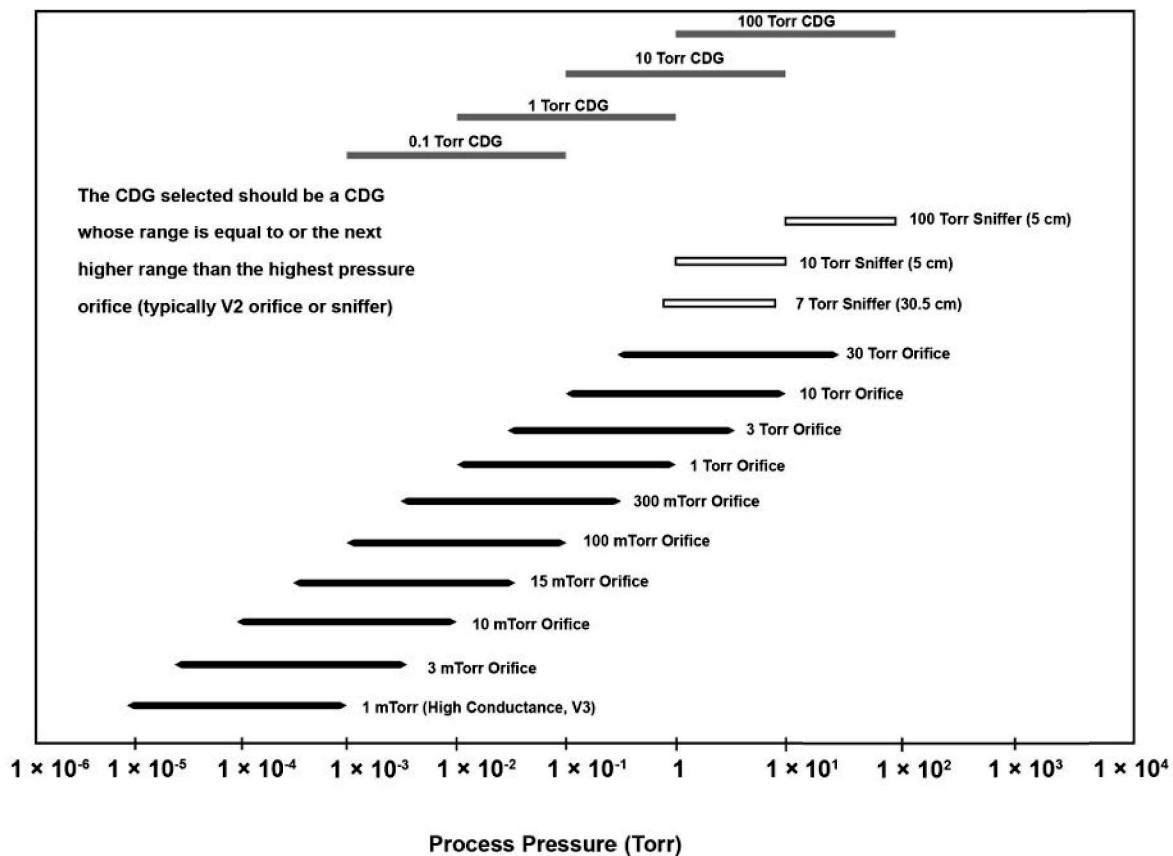


HexBlock inlets
HexBlock inlet with one orifice (V1) and high vacuum (V3)
HexBlock inlet with one orifice (V2) with high-pressure bypass (V4) and high vacuum (V3)
HexBlock inlet with two orifices (V1) and (V2)
HexBlock inlet with two orifices (V1) and (V2) with high-pressure bypass (V4)
HexBlock inlet with two orifices (V1), (V2) and high vacuum (V3)
HexBlock inlet with two orifices (V1), (V2) with high-pressure bypass (V4) and high vacuum (V3)

When both volume and high vacuum pump speed are constant, the orifice hole size determines the pressure at the sensor. Orifices are available in various sizes to cover several pressure ranges. The tables below show different orifices for low- and high-pressure range applications. The figure below shows pressure ranges for sampling which will assist in choosing the proper orifice for the application.

HexBlock orifices	Part Number
10 mTorr (1.3×10^{-2} mbar) orifice	923-706-G6
15 mTorr (2×10^{-2} mbar) orifice	923-706-G8
100 mTorr (1.3×10^{-1} mbar) orifice	923-706-G5
360 mTorr (4.8×10^{-1} mbar) orifice	923-706-G7
1 Torr (1.3 mbar) orifice	923-706-G4
3 Torr (4 mbar) orifice	923-706-G9
10 Torr (13 mbar) orifice	923-706-G3

Size of orifices, sniffers, and capillaries	Part Number
10 mTorr (1.3×10^{-2} mbar) orifice	923-706-G6
15 mTorr (2×10^{-2} mbar) orifice	923-706-G8
100 mTorr (1.3×10^{-1} mbar) orifice	923-706-G5
360 mTorr (4.8×10^{-1} mbar) orifice	923-706-G7
1 Torr (1.3 mbar) orifice	923-706-G4
3 Torr (4 mbar) orifice	923-706-G9
10 Torr (13 mbar) orifice	923-706-G3
30 Torr (40 mbar) orifice (requires high-pressure bypass)	923-706-G10
7 Torr (9.3 mbar) sniffer (requires high-pressure bypass, 30.5 cm length)	923-707-G3
10 Torr (13 mbar) sniffer (requires high-pressure bypass, 5 cm length)	923-707-G1
100 Torr (133 mbar) sniffer (requires high-pressure bypass, 5 cm length)	923-707-G2
30 Torr sniffer (40 mbar) (requires high-pressure bypass, 10 cm length)	923-707-G4
300 Torr sniffer (400 mbar) (requires high-pressure bypass, 5 cm length)	923-707-G5
30 Torr sniffer (40 mbar) (requires high-pressure bypass, 30.5 cm length)	923-707-G6
10 Torr sniffer (13 mbar) (requires high-pressure bypass, 30.5 cm length)	923-707-G7



8.5.2 High Pressure Sampling: Orifice Bypass (V4)

When process pressures exceed 10 Torr (13 mbar), the process gas is dense enough that the gas molecules collide with each other more often than with the walls of the sampling system. In this transition or viscous flow regime, the time constant for detecting changes in process gas composition becomes dominated by the time it takes for the gas species that changes in the process to diffuse through the gas matrix and arrive at the sampling orifice. This diffusion time is proportional to the process pressure and the square of the distance from the process to orifice. This sampling method effectively shortens the diffusion distance from process change to the sampling orifice by drawing a small quantity (8.5 ± 1 sccm) of the process gas through the sampling valve and bypass valve to the interstage port of the turbomolecular pump. When the process gas flows in this manner, the diffusion distance of the gas is reduced to about 2 cm (0.8 in.) and the response time for changes in the process gas is significantly reduced.

8.6 Advice and Tips

8.6.1 Achieving Good Base Pressure

The Transpector CPX vacuum manifold must be baked out after initial installation or whenever the RGA sensor is exposed to air. After an 8-hour bakeout and cooldown, the base pressure must be less than 5×10^{-7} Torr (6.7×10^{-7} mbar) at 40 eV, 200 μ A. If not, examine the background mass spectrum to look for the largest peak. If the spectrum is dominated by mass 18, continued bakeout is required to reduce water vapor.

8.6.2 Avoiding Trapped Gas when Sampling Valves are Closed

When V2 is closed, the sampled process pressure is trapped between V2 and the orifice installed at V2. This gas pumps out in a few minutes. It is best to keep V2 open until the process pressure is evacuated. When the process pressure is evacuated, open V1 to scan the background spectrum of the process vacuum system.



CAUTION

Close the sampling valves when finished with measurements to avoid pressure bursts to the RGA if the process is vented.



Transpector CPX turns off emission and the electron multiplier and closes all sampling valves when a pressure burst occurs.

9 Theory and Application Guide

9.1 Theory of Operation

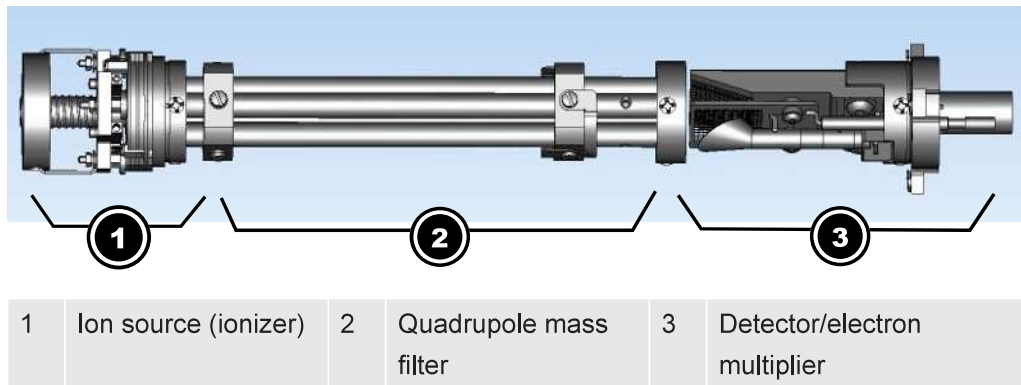
The RGA draws the gas sample to its ion source. Gas species are ionized in the ion source. These ions are focused into a quadrupole mass filter where they are filtered by their mass-to-charge ratio. The detector collects the charge from ions which have been filtered, one mass-to-charge ratio at a time.

9.2 Sensors

The three main components of the Transpector CPX sensor are:

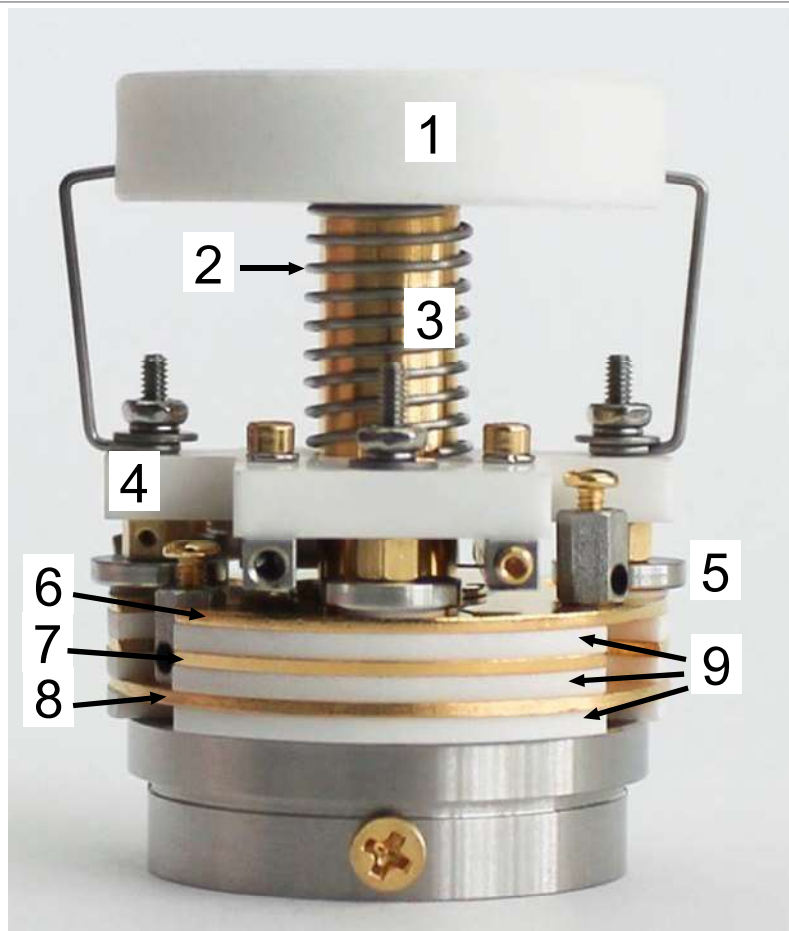
- ion source (ionizer)
- quadrupole mass filter
- detector/electron multiplier

These components are mounted on an electrical feedthrough flange bolted to the vacuum manifold. The sensor works only in a high-vacuum environment because the ions, once created, must not collide with other gas molecules as they move through the sensor.



9.2.1 Closed Ion Source

A closed ion source is the chosen ion source type for most applications above 20 mTorr (2.7×10^{-2} mbar).



1	Sealing disk	2	Spring	3	Anode cylinder
4	Filament block	5	Shield washer	6	Anode plate
7	Focus plates	8	Total pressure plate	9	Insulator ring

Inside the closed ion source, a heated filament emits electrons which bombard the incoming gas molecules and give them an electrical charge. Transpector CPX detects only positive ions. Once a molecule is charged (ionized), electric fields can be used to manipulate the molecule.

The default filament is made of tungsten. Tungsten offers the best resistance to aggressive gases, particularly those containing fluorine and chlorine. A yttria-coated iridium filament can be used in oxygen or water vapor heavy environments. Such environments would otherwise quickly oxidize a tungsten filament.



⚠ CAUTION

Filaments can be damaged when operated at high pressures or environments with incompatible chemistry.

The term emission current refers to the stream of electrons emitted by the filament. Emission current is controlled by the temperature of the filament.

The filament is centered over a hole in the anode cylinder. The potential (voltage) on the anode is positive with respect to the filament. The electron repeller, a flat plate, is located behind the filament and is electrically connected to the negative side of the filament. The potential difference between the filament and the anode determines the kinetic energy (electron energy) of the emitted electrons. The electron energy determines how gas molecules will ionize when struck by electrons.

Electron energy can range from 70 eV down to 10 eV. Operation below 70 eV is restricted to emission currents of no greater than 200 μA . At 70 eV or above, an emission current of 2 mA will maximize sensitivity for background monitoring and leak checking.

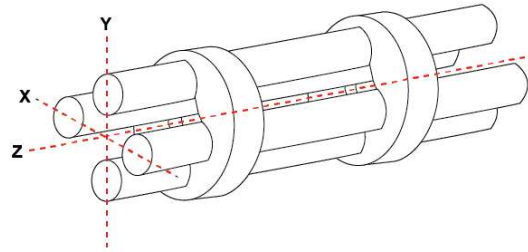
The ions formed within the ionization region are focused by the potential on the focus lens and formed into an ion beam. (The focus lens is also called an extractor, since it extracts the ions from the region in which they are created.) The focus lens focuses the ion beam into the hole in the source exit lens. To attract positive ions, the focus lens is biased negatively with respect to the anode.

The potential on the source exit lens is negative with respect to the anode and the focus lens. The ion beam passes through the hole in the exit lens and is injected into the mass filter.

9.2.2 Quadrupole Mass Filter

Ions produced in the ion source are focused into the quadrupole mass filter. RF and DC potentials are applied to the quadrupole mass filter. Each ion has a unique mass-to-charge ratio. The ratio of RF to DC potentials applied to the quadrupole dictates which mass-to-charge ratio is allowed through the quadrupole. The mass filter will step through different RF-to-DC ratios as needed to filter each mass-to-charge ratio of interest.





The mass filter's four rods (hence the term quadrupole) are alternately charged to direct ions of specific masses down through the center, deflecting all larger and smaller masses (hence the term mass filter).

The mass filter consists of four parallel rods, or poles, in a square array. The rods, and the insulators in which they are mounted, form an extremely precise mechanical assembly. The distance between the center of the square array and the closest rod surface is known as the quadrupole radius, r_0 . Ideally, the rod should have a hyperbolic shape (towards the center of the assembly) rather than round. If the ratio of the round rod radius to r_0 is equal to 1.148, the resulting electric field is a reasonably good approximation of the desired hyperbolic shape.

Opposite rods are electrically connected together. The ions are directed into the space between the poles in a direction nominally parallel to the length of the rods. There the ions are separated according to their mass-to-charge ratios by the lateral forces resulting from the potentials applied to the poles.

The applied potentials consist of an RF component and a DC component. The RF potential on one set of rods is out of phase by 180° with respect to the RF potential on the other set of rods, but all are the same amplitude. For one pair of rods, the "X" pair, the DC potential is positive. For the other, the "Y" pair, the DC potential is of the same magnitude but negative. The DC and RF potentials are referenced to a center voltage (pole zero).

The following equations summarize the potentials applied to the rods:

$$X = V_{\cos}(2\pi ft) + U + PZ \quad [1]$$

$$Y = V_{\cos}(2\pi ft + \pi) - U + PZ \quad [2]$$

V = RF amplitude

f = RF frequency

t = time

U = DC potential

PZ = pole zero

The RF component removes the low-mass ions from the beam. Ions of sufficiently low mass have their motions remain in phase with the applied RF. These ions will gain energy from the field and oscillate with increasingly large amplitudes. Eventually, as they travel along the length of the rods, they will strike one of the rods and be neutralized. High-mass ions are focused by the RF component to an area close to the quadrupole's long axis, the z axis.

The DC component is superimposed on the RF to remove high-mass ions from the beam. The DC field deflects the high mass ions toward the negative poles, opposing the focusing effects of the RF field. Eventually, these high-mass ions strike the negative rods and are neutralized. By a suitable choice of DC-to-RF ratio, the mass filter can be made to discriminate against both high- and low-mass ions. The ion energy directed along the z axis of the mass filter is dependent on the difference between the potential at which the ions were formed (the anode voltage) and the pole zero.

The ion energy is usually only slightly modified by the electric field (the fringing field) between the source exit aperture and the quadrupole. Imbalances in the amplitude of the two phases of RF applied to the rod pairs, and DC voltages are also applied, resulting in a further modification of the ion energy.

The mass of the ions passed by the filter is determined by the RF amplitude, the RF frequency, and the quadrupole radius:

$$V = 14.438M^2f^2(r_0)^2 \quad [3]$$

V = peak-to-peak RF amplitude in volts

M = mass of the ion in atomic mass units (amu) per electron charge

f = RF frequency in megahertz

r_0 = quadrupole radius in centimeters

For example, a 200 amu singly charged ion would pass through a quadrupole with nominal 6.35 mm (1/4 in.) diameter rods (an r_0 of 0.277 cm), operating at 1.78 MHz, at a peak-to-peak RF amplitude of approximately 700 V.

The mass of ions transmitted (M) is directly proportional to the RF amplitude (provided f is constant). As the RF amplitude is increased, progressively higher mass ions will be made to oscillate in phase with the RF field and thus gain sufficient energy to strike the poles. The DC voltage must be increased to maintain the high-mass rejection properties of the filter. A mass spectrum is generated by sweeping the RF amplitude along with the DC voltage.

The next section (Scanning Characteristics [▶ 57]) discusses the variation in the efficiency of transmission of ions through the filter with mass. The Zero Blast [▶ 57] discusses the behavior of the filter at very low masses where the applied voltages approach zero.

9.2.2.1 Scanning Characteristics

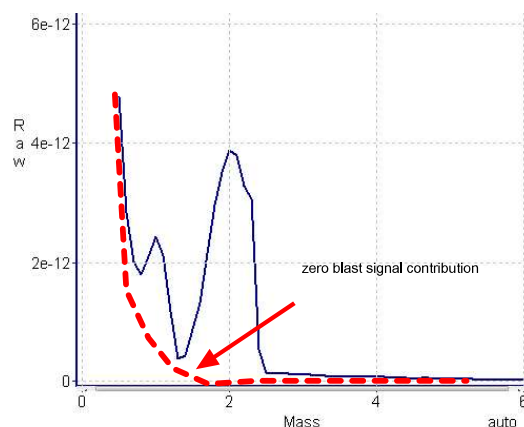
The quadrupole acts as a pass-band mass filter for a mixed beam of ions in normal operation, rejecting ions outside of the pass band and allowing ions with mass-to-charge ratios inside the pass band to travel to the detector. The selectivity of the mass filter is expressed in terms of resolution, R , which is numerically given by the ratio of the center mass-to-charge ratio, M , to the width, ΔM (both unitless), of the pass band. Since the number of the ions passed by the filter falls off gradually as the edge of the pass band is approached, the width is defined at the point where the ion current falls to some specified fraction (usually 1/2 or 1/10) of the maximum value. The width of the pass band is determined by the DC-to-RF ratio.

The quadrupole can be designed so that R varies in any desired manner with M . However, keeping ΔM constant ensures adequate separation of ions that are 1 MU apart. This mode of scanning is called Constant ΔM . As a result, R is proportional to M , and therefore the efficiency with which ions of mass M are transmitted through the quadrupole decreases with M . Therefore, the sensitivity of the sensor decreases as M increases.

9.2.2.2 The Zero Blast

When the RGA scans over the very low end of the mass spectrum, the RF and DC voltages applied to the rods approach zero. The quadrupole then ceases to act as a filter and a large current of unseparated ions is detected, called the zero blast.

Zero blast will interfere with the observation of masses 1 and 2 in the higher-pressure range of the RGA [for example, 1×10^{-6} to 5×10^{-4} Torr (1.3×10^{-6} to 6.7×10^{-4} mbar)] when significant quantities of higher-mass ions are present. The zero blast contribution to the mass 2 signal intensity can be between 5 and 100 ppm depending on the mass range of the RGA.



9.2.2.3 The Ion Detector

The ion detector region of the sensor consists of the quadrupole exit lens, the electron multiplier, and the detector itself. The quadrupole exit aperture is biased negatively with respect to the anode, focusing ions that have been transmitted through the quadrupole into the electron multiplier and detector.

9.2.2.3.1 The EM Detector

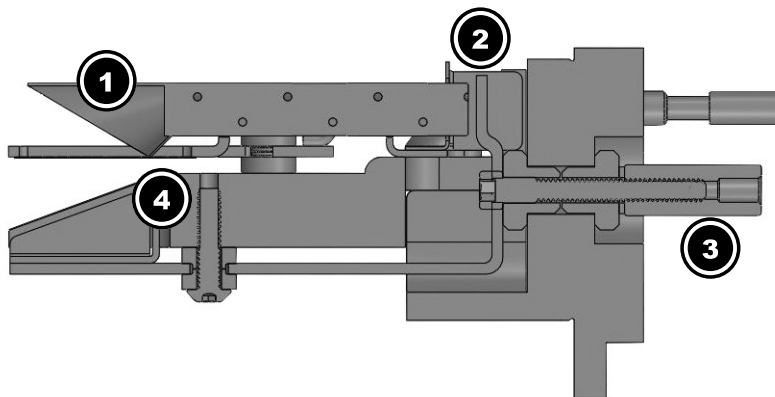
The electron multiplier (EM) acts as an in situ preamplifier for improved sensitivity. Incoming ions are accelerated into the EM by a high negative voltage (usually -1.0 kV or more). When an ion strikes the surface of the EM, one or more secondary electrons are emitted. These electrons are accelerated to a second surface which is at a more positive potential, where additional electrons are generated.

This process repeats itself until a pulse of electrons emerges from the output of the EM and is collected in a Faraday cup. The result is that as many as a million electrons or more can be produced by each incident ion. The current output from an EM detector is negative due to this pulse of electrons.

The ratio of the electron output current to the incident ion current is the EM gain. The gain primarily depends on the EM type, the voltage applied to the EM input, the voltage applied across the EM, the condition of the EM, and, to a lesser extent, the mass and chemical nature of the incident ion. In general, EM gain decreases as the ion mass increases. The advantage of the EM detector sensor is its high sensitivity (as much as 500 A/Torr), making it possible to measure partial pressures as low as 1×10^{-15} Torr (1.3×10^{-15} mbar) for a 100 amu sensor.

9.2.2.3.2 The Continuous Dynode Electron Multiplier/Faraday Cup Detector

The continuous dynode electron multiplier/Faraday cup (CDEM/FC) detector amplifies the electron pulse, significantly increasing the analyzer's sensitivity.



1	CDEM cone	2	Electron collector
3	Signal output	4	Deflector shield

The CDEM/FC detector continuous dynode element is a special type of glass, rather than a copper-beryllium alloy that a discrete dynode EM might use. The advantage of the CDEM/FC detector over a discrete dynode EM detector is that CDEM/FC performance does not degrade when exposed to air and does not need to be stored under vacuum.

The maximum operating temperature for the CDEM/FC detector is 150°C. It can be baked out at 300°C with the high voltage off.

The CDEM/FC detector is slightly slower to recover after exposure to excessive input or output currents. It may take longer for the gain to stabilize after the high voltage is changed.

The CDEM/FC detector is operated at high voltages between -0.6 and -2.0 kV. A new CDEM/FC detector will typically have a gain between 10 and 1000 at -0.8 kV. The gain at -3.0 kV typically exceeds 1×10^6 . The Transpector CPX default EM voltage is -0.8 kV.

**⚠ CAUTION**

Do not operate the CDEM/FC detector at temperatures above 150°C. Permanent damage may result.

**⚠ CAUTION**

Avoid output currents in excess of 1×10^{-6} A. Either decrease the high voltage or decrease the pressure. Permanent damage may result.

Use the minimum CDEM/FC detector voltage required to obtain the necessary peak amplitudes and/or signal-to-noise ratio. Operating at higher voltages than necessary will result in premature aging of the EM. As the CDEM/FC detector ages, the voltage needed to obtain a specific EM gain will increase.

Since EM performance depends on the condition of its interior surfaces, prevent hydrocarbon or other contamination:

- Make sure diffusion-pumped vacuum systems are properly trapped to reduce oil back-streaming.
- Make sure turbomolecular pumped systems are interlocked to eliminate mechanical pump oil back-streaming through a nonspinning turbo pump.

EM gain reduction from these kinds of problems can range from 50% to more than 90%. The initial gain of the EM is generally high enough to accommodate some degradation and still be usable. With repeated instances of contamination, the EM will eventually require replacement.

**⚠ CAUTION**

In addition to hydrocarbon contamination, an EM can be adversely affected by exposure to highly reactive chemicals.

Avoid any substance that will either cause the deposition of a surface film on the EM or etch its surface. Avoid high levels of reactive fluorides, such as tungsten hexafluoride, hydrogen fluoride, and nitrogen trifluoride.

10 Operation

10.1 HexBlock

HexBlock provides several inlets, a process pressure gauge (CDG), and a calibration reference. It allows for up to three pressure ranges, including a high conductance inlet that covers various applications such as high-density plasma etch (HDP), TiN Deposition such as TDMAT, W CVD, or any other semiconductor process.

Advantages include:

- Small vacuum path lengths
- Minimum surface area
- Interchangeable orifices
- Multiple process connection options (CF40, KF40, and KF25)
- Multiple sniffer (capillary) inlet options for sampling the process

The orifices mounted in the HexBlock valves are replaceable.

Pressure ranges for the two main sampling valves are:

- V1: 3 mTorr to 10 Torr (4×10^{-3} to 13 mbar)
- V2: 3 mTorr to 760 Torr (4×10^{-3} mbar to 1 bar)



CAUTION

The tool and Transpector CPX must be vented before changing orifices, except when a tool isolation valve is installed.

10.1.1 HexBlock Inlet

- V1 allows low pressure sampling (LP). It also indicates the background pressures for some etch or CVD processes. No bypass is available.
- V2 allows high pressure sampling (HP). It also indicates process pressures for etch, CVD, and 300 mm degas sampling. Bypass is optional.
- V3 is for high conductance (HC). It is similar to a wide open position. V3 is used for any high vacuum condition lower than 1 mTorr (1.3×10^{-3} mbar).
- V4 is for bypass. V4 is used in conjunction with V2 in high pressure applications [above 1 Torr (1.3 mbar)]. V4 connects to the interstage of the turbomolecular pump via a bypass tube which pulls gas from the process directly to V2. This can cut the response time down from several minutes to less than 10 seconds for a 100 Torr (133 mbar) process. The V4 bypass inlet typically consumes approximately 17 sccm of process gas.



When sampling lighter gases such as hydrogen and helium, it may be necessary to connect the V4 bypass tube to the foreline pump port rather than the turbomolecular pump interstage port to improve pumping efficiency.



CAUTION

To prevent pressure bursts to the RGA, V4 should open before V2 to ensure the pressure is correct for the V2 orifice.

When V2 is closed, V4 should remain open for several seconds to pump out residuals left from sampling the process.

- V5 is a calibration reference. The calibration valve refers to the option of adding a calibration reference to the Transpector CPX system. The calibration reference is located near the ion source. V5 is used for mass tuning and as a sensitivity reference, providing:
 - A means to tune the RGA
 - A reference for adjusting the EM voltage
 - A way to check whether the orifices are getting dirty or clogged
 - A reference for tracking the performance of the RGA



The Transpector CPX emission and EM are turned off prior to opening the calibration valve (V5). This is due to trapped gas in the calibration reference.

- The sniffer or capillary option allows sampling closer to the actual process reactions and it gives a faster response time and better signal (uses valve V2). Capillaries also provide part of the necessary pressure drop to sample from atmospheric pressure.
- The CDG gauge measures process pressure. It helps to prevent accidental or erroneous inlet valves from being opened at suboptimal or unsafe pressures.

10.1.2 HexBlock Process Connections

Types of connections	Part Number
KF25 in-line connection	923-700-G1
KF40 in-line connection	923-701-G1
CF40 in-line connection	923-702-G1
KF25 90 degree elbow connection	923-703-G1
KF40 90 degree elbow connection	923-704-G1
CF40 90 degree elbow connection	923-705-G1

10.1.3 Calibration Option

A single source of gas mixture accomplishes two calibration functions:

- Mass scale calibration
- Partial pressure reference levels



Selection of the appropriate gas mixture components is dictated by the mass range desired.

The composition of the Calibration Reference option is shown in the table below. The method of delivery is a flow reference with a remote on/off valve (V5). The gas flow rate is calibrated at the factory and is kept small [typically 1×10^{-4} Torr·L/s (1.3×10^{-4} mbar·L/s)] by a sintered leak. Flow through the leak element is viscous, therefore the gas composition in the reservoir is not altered by sampling. To ensure that no calibration mix enters the tool, the pumping system does not allow other valves to open with the calibration reference.

Component (composition)	Calibration masses
H ₂ (1%)	2
He (1%)	4
N ₂ (1%)	28
Ar (balance)	36, 38, 40
Kr (1%)	84
Xe (1%)	134, 136



Refer to the software operating manual for more information regarding mass tuning. Results using FabGuard with this calibration mixture may be different than shown above due to the programming of the ionization probability and material factors.

10.1.4 Process Gauge

The CDG measures the pressure based on the elastic deformation of a ceramic diaphragm. The capacitance change caused by the deflection is converted into a linear output signal proportional to pressure.

The CDG is resistant to high-pressure surges. The CDG type is selected based on process conditions. See the table below. Select a gauge based on maximum pressure orifice. The CDG range must be equal to or the next higher range than the highest-pressure orifice (typically V2 or the sniffer).

Process range	Part Number
1 Torr (1.3 mbar) range	964-208-G11
10 Torr (13 mbar) range	964-208-G12
100 Torr (133 mbar) range	964-208-G13
1000 Torr (1330 mbar) range	964-208-G14

10.2 Heaters

A Transpector CPX software interlock only allows for heater operation when the turbomolecular pump is at normal speed (90,000 rpm). The temperature is programmable through FabGuard application software.



WARNING

To avoid burn hazard and for proper operation of heaters, heater covers should always be installed when operating heaters.

10.3 Pumping System

The pumping system is preconfigured at the factory. The pumping system can be reconfigured with a different:

- Foreline pump, either system controlled or customer supplied
- Turbomolecular pump, either standard or corrosive
- Inlet arrangement, the type of inlet and/or orifices

10.3.1 Foreline Pump

The system controlled foreline pump configuration is selected when there is an INFICON-supplied foreline pump. If a customer-supplied foreline pump is used to back other vacuum equipment, a check valve should be used to temporarily isolate Transpector CPX from any short (<10 s) pressure bursts that would damage Transpector CPX.



CAUTION

A customer-supplied pump must supply a continuous foreline pressure below 12 Torr (16 mbar).

10.3.2 Foreline Pirani Gauge

A Pirani gauge mounted to the Transpector CPX foreline monitors the pressure in the foreline. In the event of a pumping system malfunction, the foreline Pirani gauge will indicate a pressure >12 Torr (16 mbar) and shut down the system. For optimal pumping system performance, the foreline pressure should be <2.25 Torr (3 mbar).

10.3.3 Turbomolecular Pump

There are two types of pumping systems: standard (noncorrosive) and corrosive. The same standard turbomolecular pump is used in both applications.

The corrosive pump configuration is selected for applications such as CVD or etch or whenever corrosive gases are being sampled. The purge valve is automatically opened when the Transpector CPX turbomolecular pump is operating.

The corrosive pumping system provides purge gas flow through the bearing region of the turbomolecular pump to protect the bearings from corrosion and loss of bearing lubricant by evaporation. The regulator is preset at the factory to produce 8.5 ± 1 sccm of nitrogen purge.



⚠ CAUTION

For the corrosive service turbomolecular pump (CVD/etch), nitrogen purge gas is required whenever the system is operational.



⚠ WARNING

The turbomolecular pump must be completely at rest and the electronics power supply must be disconnected before removing the turbomolecular pump connecting cable.

10.3.3.1 Turbomolecular Pump Status

Pump rotational speed is the revolutions per minute (rpm) at which the turbomolecular pump is operating. Full speed is 90,000 rpm.



⚠ CAUTION

With the corrosive turbomolecular pumping system, a nitrogen purge valve with regulator is connected to the purge port of the pump.

The nitrogen purge valve is always open when the corrosive turbomolecular pump is running. This protects the bearings from corrosive gas attack and evaporation of the bearing lubricant.

10.4 Nitrogen Purge Valve for the Turbomolecular Pump on Corrosive Pumping Systems

On corrosive pumping systems, the nitrogen purge valve provides a continuous flow of dry nitrogen to the bearings of the turbomolecular pump.

The nitrogen purge valve opens when the turbomolecular pump is turned on and closes when the pump is shut down.

10.5 Filament Control

10.5.1 Interlock

On pumpdown, emission automatically turns on when the turbomolecular pump reaches full speed (90,000 rpm). The emission automatically turns off if the pump controller determines the turbomolecular pump is no longer up to speed.

10.5.2 Total Pressure Calibration

To protect the filament, Transpector CPX has a factory-calibrated total pressure lens that measures the total pressure in the closed ion source (CIS). The filament turns off (within 50 ms) after the pressure in the ion source rises above the total pressure set point, typically 1×10^{-3} Torr (1.3×10^{-3} mbar) at 40 eV and 200 μ A for a CIS.

The total pressure reading is calibrated with the ionizer set at both the default low emission settings (200 μ A emission; 40 eV electron energy) and default high emission settings (2 mA at 70 eV). The default value for the overpressure set point is 1 to 3 mTorr (1.3×10^{-3} to 4×10^{-3} mbar).

When sampling at process pressures, running at high emission will result in poor linearity if the overpressure does not trip. If 70 eV is desired for monitoring process gas, in FabGuard enter **Sensor Configuration** and change the electron energy to 70 eV, leaving the emission current at 200 μ A.

Recalibration requires calculation of the pressure in the CIS when the process gas is introduced at a known pressure. The relationship is:

$$P_{\text{CIS}} = C_{\text{Orifice}} P_{\text{Process}} / C_{\text{CIS}} \quad [4]$$

The table below lists the values for the exit conductance for single-filament closed ion source (SF-CIS) and for different orifices used in Transpector CPX sampling systems. Equation [4] can be used to infer the target gas pressure in the CIS that produces the total pressure measurement. Using the process gas pressure (measured by the CDG

or other gauge) and the conductance of the orifice in use, the P_{CIS} value can be calculated to use the automatic Total Pressure Calibration option in FabGuard software.

Orifice designation	Nominal orifice diameter (μm)	Conductance (L/s)	PCIS (Torr) [@ design $P_{Process}$]
CVD-CIS Exit	N/A	1.0	N/A
10 mTorr (1.3×10^{-2} mbar)	675	3.9×10^{-2}	3.9×10^{-4}
100 mTorr (1.3×10^{-1} mbar)	170	2.8×10^{-3}	2.8×10^{-4}
1 Torr (1.3 mbar)	55	2.7×10^{-4}	2.7×10^{-4}
3 Torr (4 mbar)	31	8.6×10^{-5}	2.6×10^{-4}
6 Torr (8 mbar)	22	4.4×10^{-5}	2.6×10^{-4}
10 Torr (13 mbar)	18	2.8×10^{-5}	2.8×10^{-4}

10.5.3 Filament Lifetime

Tungsten filament material is used in corrosive applications. The melting point of tungsten is 3410°C (6170°F); its boiling point is 5660°C ($10,220^{\circ}\text{F}$). At normal operating temperatures [approximately 2200°C (4000°F)], tungsten vapor pressure is approximately 1×10^{-7} Torr (1.3×10^{-7} mbar), which normally results in a reasonable lifetime. Various oxides of tungsten are known.

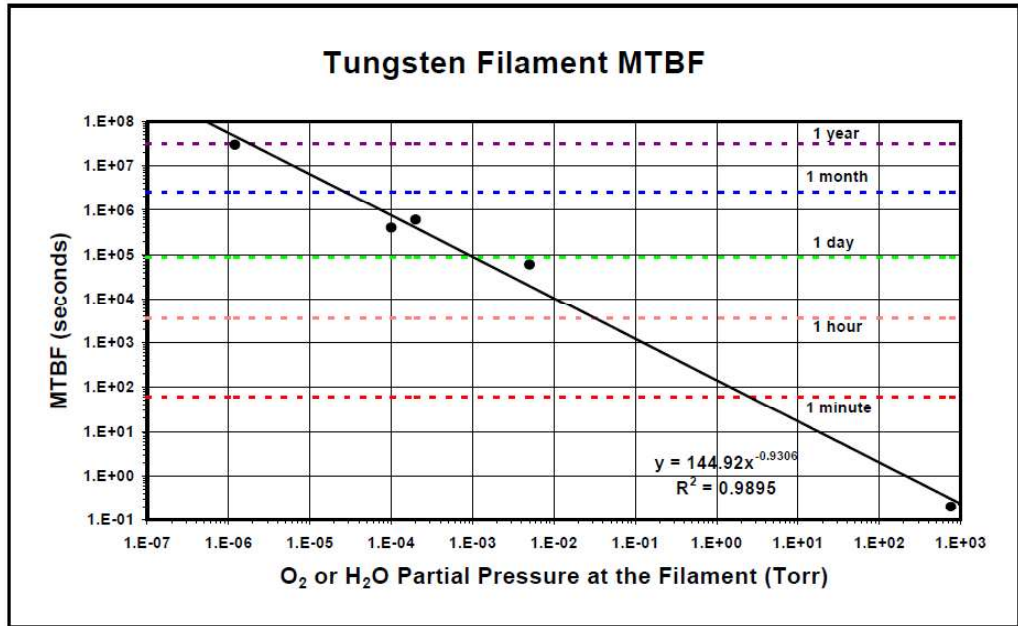
The lowest oxide, WO_2 , is brown in color and has a sublimation temperature of around 800°C (1470°F). The intermediate oxides, W_2O_5 and W_4O_{11} , which are blue-violet in color, and sublimes between 800 and 900°C (1470 and 1652°F).

The highest oxide, WO_3 is yellow in color and has a melting point of 1473°C (2680°F). No boiling point or sublimation temperature is reported, but presumably it is far more volatile than the pure metal itself.

At normal filament operating temperature, tungsten readily reacts with oxygen or water vapor to form oxides.

- If the oxygen (or water vapor) is very high, WO_3 is formed. This would be observed if an attempt had been made to turn on the filament in air at 760 Torr (1 bar).
- At lower oxygen (or water vapor) partial pressures, lower tungsten oxides are formed, giving rise to the blue color observed on the electron repeller. Since the tungsten oxides are far more volatile than the pure tungsten, when they form on the filament surface, they evaporate away, depositing on the nearest relatively cool surface.

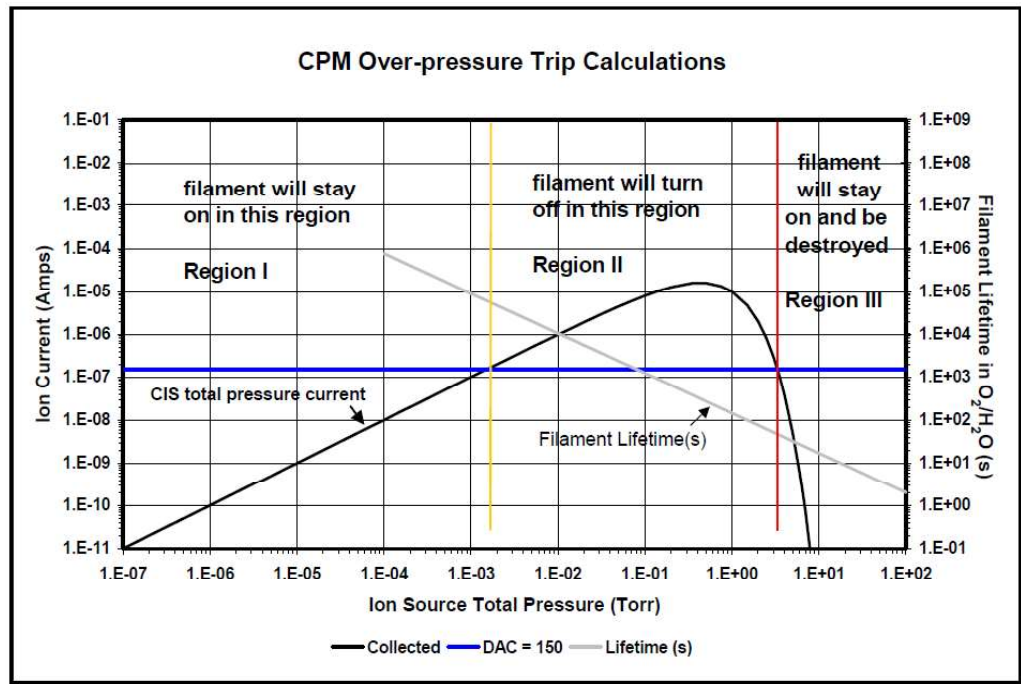
The figure below depicts a graph correlating tungsten filament mean time between failure (MTBF) in seconds with oxygen or water vapor partial pressure in Torr. The graph predicts a filament lifetime of approximately 200 seconds at 1 Torr (1.3 mbar), the maximum pressure at which Transpector CPX can maintain electron emission.



At 1 Torr (1.3 mbar) at the filament, the pressure inside the anode cylinder will be approximately five times higher (assuming the bulk of the gas load is entering the Transpector CPX manifold through the closed ion source).

At 5 Torr (6.7 mbar), the collisional mean free path for ions will be less than 0.01 mm (4×10^{-4} in.). The distance from the ion creation region to the total pressure collector electrode is about 4 mm (0.16 in.), or approximately 400 mean free paths away. At this pressure, the scattering losses may sufficiently reduce the total pressure ion current so that it remains less than the overpressure trip current. Under these conditions, the filament would stay on and react with the oxygen, producing relatively volatile tungsten oxides, until the filament diameter had been reduced to the point where the tension on the wire was sufficient to cause the wire to pull apart.

The figure below depicts a Transpector CPX overpressure trip calculation. The total pressure current curve after 5×10^{-1} is due to the pure collisional scattering. Without collisional scattering, it will be linear. The point where the CIS total pressure current and DAC line meet is called the overpressure trip point. When the total pressure current exceeds the digital-to-analog converter (DAC) line (Region II) the filament is turned off.



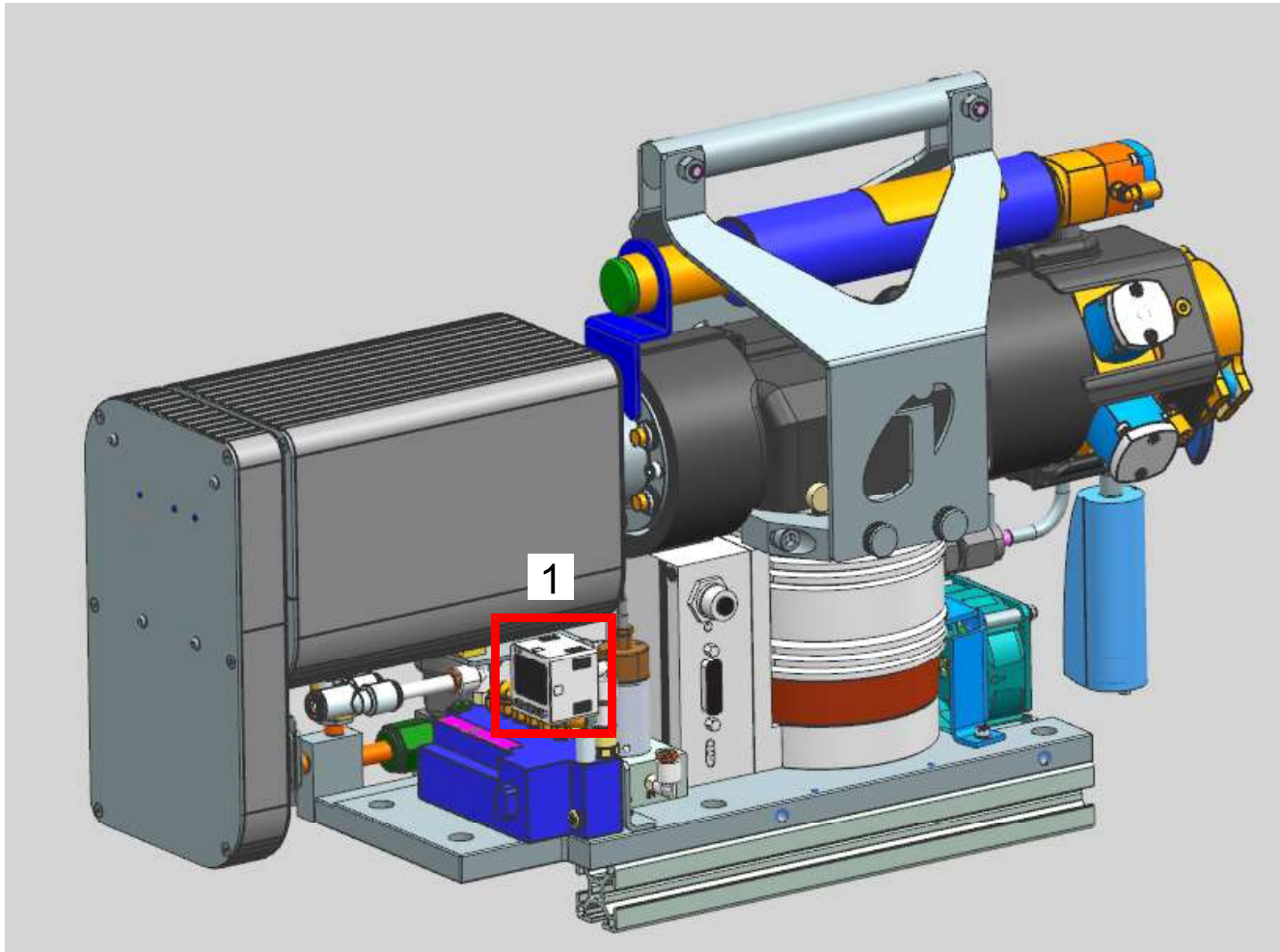
In Region II, there is a six-second delay in turning emission on and off.

At 5 Torr (6.7 mbar) in Region III, there is no overpressure and no emission error, but the filament will last only hours. At 100 Torr (133 mbar), the filament would be destroyed instantly.

10.6 Pneumatic Digital Pressure Switch and Pressure Gauge

The pneumatic digital pressure switch and pressure gauge:

- Provides a visual display of the air (or nitrogen) pressure provided to the pneumatic block.
- Ensures a proper pressure for the Transpector CPX to function. If the pressure decreases below 58 psi (4 bar) (400 kPa) or exceeds 120 psi (8.27 bar) (827 kPa), the Transpector CPX system shuts itself down.



1

Pneumatic digital pressure switch and gauge

11 Diagnosing Problems

Downtime can be reduced by diagnosing problems from observations related to the failure, examining the FabGuard event logs, and checking the hardware status.

11.1 Communication Problems

To correct communication problems, check the following:

- Is the Ethernet cable connected to the Transpector CPX electronics module and the host computer (either directly or through a router/switch)?
- Does the Transpector CPX IP address have the same network prefix as the host computer?
- Is Port 80 open on the host computer?
- Is there an IP address conflict between Transpector CPX and another network device?

11.2 If You Cannot Resolve Your Problem

If you cannot resolve your problem, contact INFICON.

See Service and Technical Support [▶ 92]

11.3 Event Log Files

FabGuard software records errors and events, along with the time of occurrence, for each day of operation, providing a chronology of operations that can be useful in diagnosing problems. See the FabGuard Operating Manual for additional information.

12 Maintenance

12.1 Introduction

The Transpector CPX sensor is subject to aging with normal use and some of its components will eventually require repair or replacement.

INFICON provides complete maintenance service for Transpector CPX electronic modules, Transpector CPX sensors, and the pumping system.



WARNING

Performing maintenance tasks on the Transpector CPX sensor should only be done by qualified personnel.

12.2 Safety Considerations

If Transpector CPX is used in a manner not specified by INFICON, protection provided by the equipment may be impaired.

12.2.1 Toxic Material

The Transpector CPX sensor does not contain any toxic material. However, if the Transpector CPX sensor is used in an application wherein toxic material is used or generated, residue of the toxic material will likely be present on the surface of the Transpector CPX sensor. Appropriate safety precautions must be taken when handling contaminated sensors in order to assure safety of maintenance personnel.

The Transpector CPX electronics module is Restriction of Hazardous Substances (RoHS) compliant.

12.2.2 Radiation

Transpector CPX gas analysis systems are not known to produce harmful radiation.

12.2.3 Electrical Voltages

Transpector CPX does not present electrical hazards when enclosed and grounded according to the specifications given in the installation instructions.



⚠ WARNING

If the Transpector CPX electronics module is operated while open, hazardous electrical voltages may be present. Such operation should only be performed by qualified service personnel.

12.3 General Instructions for All Maintenance Procedures



⚠ CAUTION

- Perform any service in a clean, well-illuminated area.
- Obey all cautions and warnings.
- Wear clean, nylon, lint-free lab gloves or finger cots.
- Do not touch the vacuum side of the sensor with unprotected fingers.
- Use clean tools for sensor disassembly and assembly.

12.4 Bakeout of Quadrupole

If the symptoms suggest that the sensor is contaminated, try first to restore normal performance by baking the sensor under a high vacuum [1×10^{-5} Torr (1.3×10^{-5} mbar) (1.3×10^{-3} Pa) or lower] for several hours, preferably overnight. The table below shows the maximum bakeout temperatures.

If baking the sensor does not improve the sensor performance, it may be necessary to perform the tasks described in Filament Kit Replacement [▶ 75] and Ion Source Replacement [▶ 78].

If the procedures explained above do not solve the problem, contact INFICON.

		While operating	With electronics removed
Electron multiplier–Faraday cup combination	EM Mode	150°C	300°C
	FC Mode	200°C	300°C



⚠ CAUTION

When heating the sensor above 200°C, the electronics module must be removed from the sensor.

12.5 Maintenance Procedures

12.5.1 Tools Required

Tools for Replacing the Filament Kit

- Ohmmeter
- 3.2 mm nut driver
- 1.5 mm (1/16 in.) flat blade screwdriver
- 0.9 mm (0.035 in.) hex driver
- Nonmetallic precision tweezers

Tools for Replacing the Ion Source

- Ohmmeter
- 1.5 mm (1/16 in.) flat blade screwdriver
- 0.9 mm (0.035 in.) hex driver
- #1 Phillips head screwdriver
- Nonmetallic precision tweezers

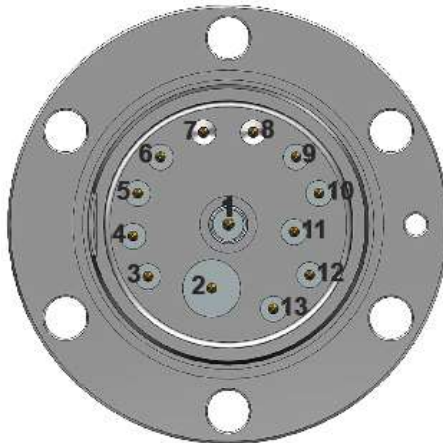
Tools for Replacing the Electron Multiplier

- 1.5 mm (1/16 in.) flat blade screwdriver
- #1 Phillips head screwdriver
- 1.5 mm × 50 mm hex driver
- 2.0 mm × 75 mm hex driver
- Nonmetallic precision tweezers

12.5.2 How to Determine if a Filament Replacement is Required

Follow these steps to determine if a filament replacement is required.

- 1 Measure the resistance of each filament. This can be accomplished while the sensor is under vacuum by measuring the resistance between pins **3** and **10**. A failed filament will measure **open** while an intact filament will measure between 0.2 and 0.8Ω.





Although the following measurements may measure below 30 MΩ with the filament assembly and ceramic shield in place, they must be above 30 MΩ when measured with the filament assembly and ceramic shield removed.

- 2 Measure the resistance of each of the pins with respect to ground (pins **7** and **8**). These measurements must be above 30 MΩ.
- 3 Measure the resistance of each of the pins with respect to each other. All of these measurements must be above 30 MΩ, with the exception of measurements between each filament pin and the filament common pin if the filaments have not failed.

Pin	Assignment
1	PP
2	EM HV
3	Filament
4	Reserved
5	Anode
6	RF-
7	GND
8	GND
9	RF+
10	Filament Common
11	Reserved
12	Focus
13	TP

12.5.3 Filament Kit Replacement

Perform the following steps to replace the filament. Use nonmetallic precision tweezers throughout replacement to aid in handling small parts.

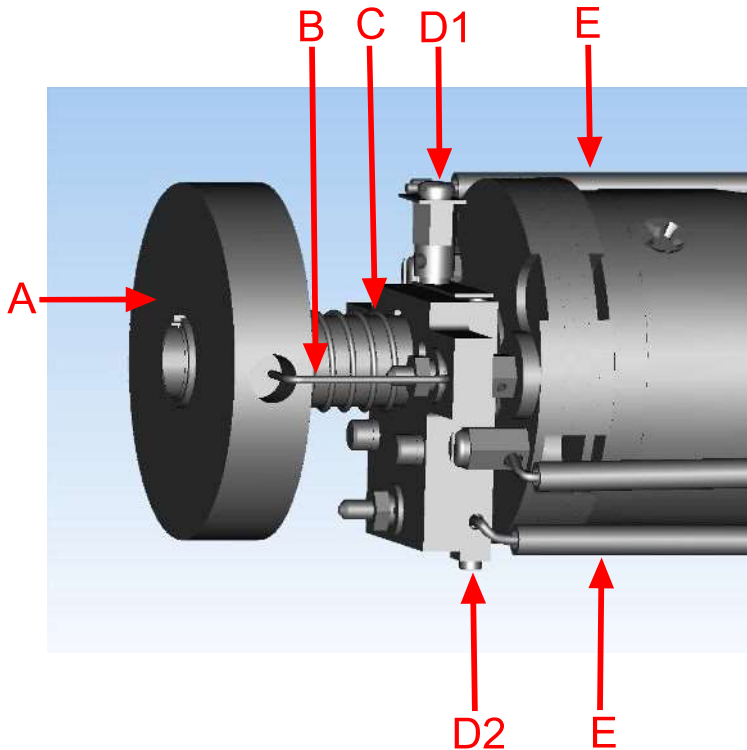


⚠ CAUTION

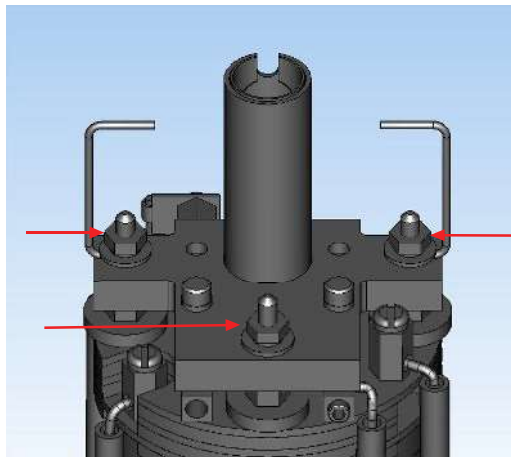
Neither the filament assembly nor the ion source can be cleaned. When dirty, these components must be replaced.

✓ Refer to Tools Required [▶ 74] before continuing.

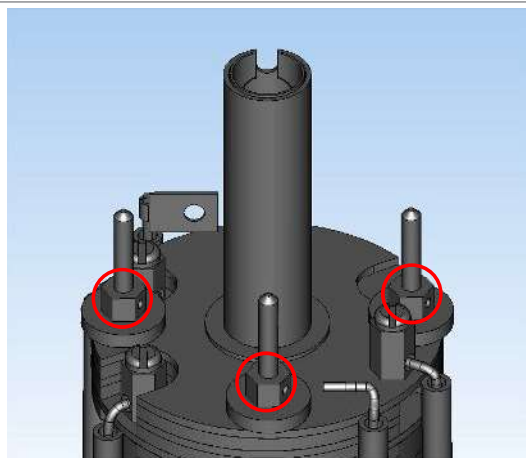
- 1 Remove the ceramic sealing disk (A) by carefully pulling the wire hold-downs (B) away from the edges of the disk and pulling off the sealing disk.
- 2 Remove spring (C).
- 3 Remove the filament lead screw and washer (D1) using a 1.5 mm flat blade screwdriver, loosen the filament lead screw (D2) using a 0.9 mm hex driver, and remove the filament leads (E) from the filament.



- 4 Remove the three nuts and washers holding the filament assembly in place using a 3.2 mm nut driver. Be careful; do not lose the two ceramic sealing disk wire hold-downs.



- 5 Carefully remove the filament assembly.
- 6 Remove the three screws holding the filament assembly on the shipping fixture.



- 7 Carefully remove the new filament from its fixture and place it on the ion source posts.
- 8 Replace the three filament assembly nuts and washers. Be sure to install the wire hold-downs.



⚠ CAUTION

To avoid cracking the ceramic plate, do not overtighten the three nuts.

- 9 Reattach the filament leads and tighten the filament lead screws.
- 10 Reinstall the spring and the ceramic sealing disk.
- 11 Using an ohmmeter, check that the filament is not shorted to ground and that the filament shows a resistance of approximately 1Ω at the feedthrough.
- 12 Connect the RGA to FabGuard software and go to **Sensor Hardware Configuration**, view the **Lifetime** section, and select **Reset** for **Emission Filament (h)**.

Parameter	Value	
Sensitivity and EM calibration Type	Specific mass	
Sensitivity mass (AMU)	28	
Sensitivity target (AP)	0	
EM mass (AMU)	28	
EM target Gain	0	
EM target Signal (A)	0	
EM target Signal/Pressure (AP)	0	
EM calibration Gain (perform calibration to set)	0	
Life Time		
Power (h) (time until next maintenance)	0 (277777)	Reset
Emission Filament (h) (time until next maintenance)	0 (277777)	Reset
Electron Multiplier (h) (time until next maintenance)	0 (277777)	Reset
Plot		
Unit	Rew	
Tag Scan Subtract	None	
Scan X axis type	Linear	
Scan Y axis type	Linear	
Trend X axis type	Linear	
Trend Y axis type	Linear	

- 13 Reset the Emission Filament (h) to zero.



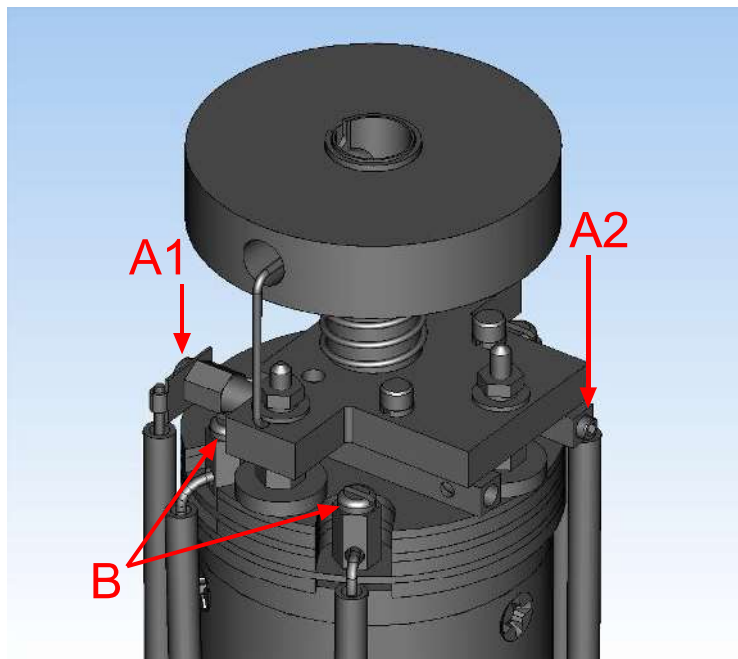
It is required to perform sensor tuning, calibrate Faraday sensitivity, and calibrate sensitivity and EM gain before using the RGA.

12.5.4 Ion Source Replacement

Proceed as follows to replace the ion source. Use nonmetallic precision tweezers throughout replacement to aid in handling small parts.

✓ Refer to Tools Required [▶ 74] before continuing.

- 1 Remove filament lead screw (A1) using a 1.5 mm flat blade screwdriver, loosen filament lead screw (A2) using a 0.9 mm hex driver, and loosen the three screws (B) using a 1.5 mm flat blade screwdriver.



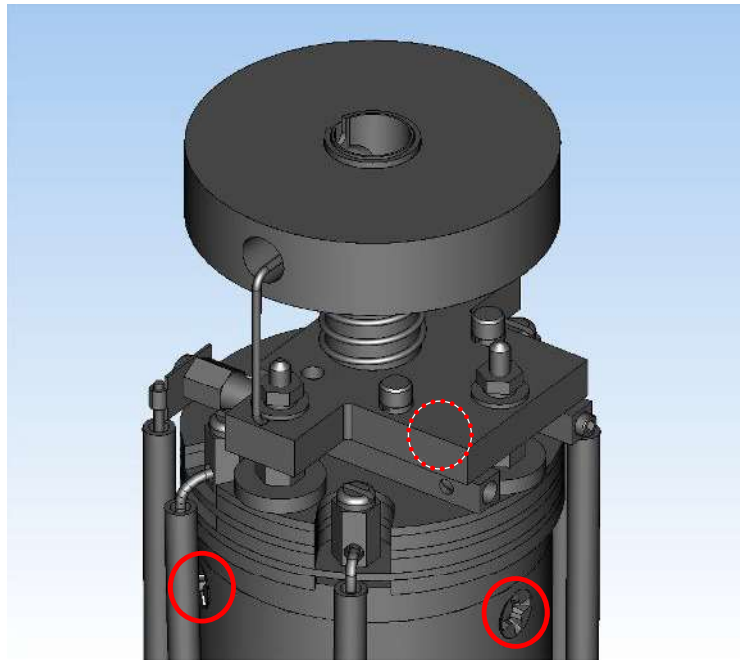
- 2 Pull the electrical leads away from the sensor.



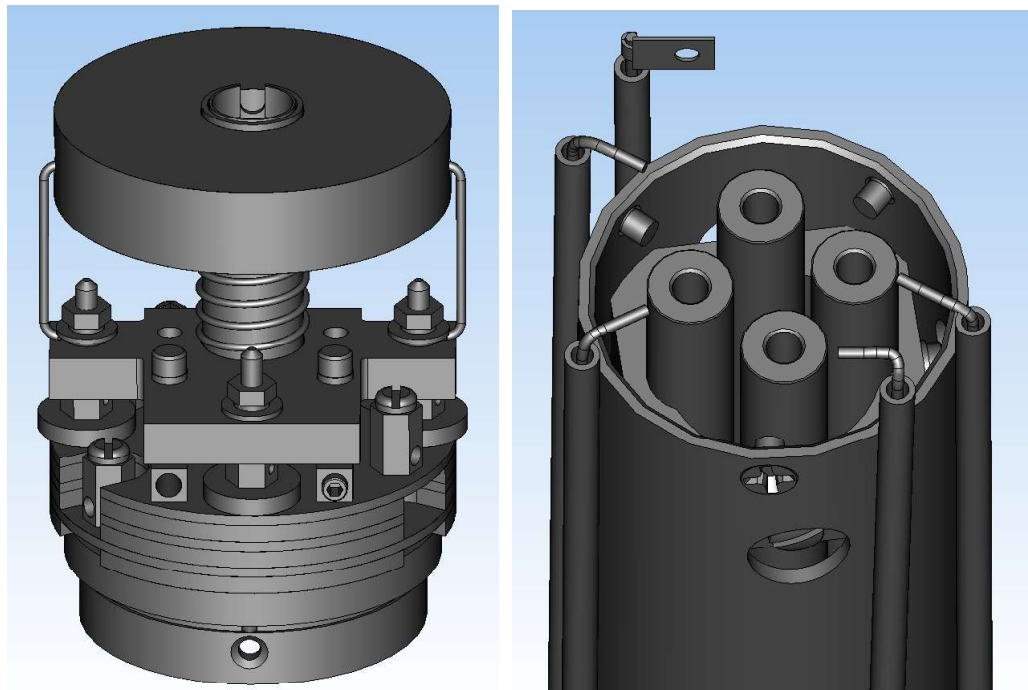
⚠ CAUTION

Do not bend the leads.

- 3 Remove the three ion source retaining screws (circled in red, one is hidden in the figure) around the bottom of the ion source assembly using a #1 Phillips head screwdriver. They hold the ion source onto the mass filter.



- 4 The ion source can now be removed by lifting it off the mass filter. Install a new ion source by reversing the above steps.



- 5 Using an ohmmeter, check:
- ⇒ that the filament is not shorted to ground or to any of the ion source plates.
 - ⇒ that the two filament leads show a filament resistance of approximately 1Ω at the feedthrough (approximately 0.5Ω at the lead connectors). See the image below for pin-out locations.

- 6 Connect the RGA to FabGuard software and go to **Sensor Hardware Configuration, Lifetime** section, and select **Reset** for **Emission Filament (h)**.
- 7 Reset the Emission Filament (h) to zero.



It is required to tune the mass-scale table, calibrate Faraday sensitivity, and calibrate sensitivity and EM gain before using the RGA.



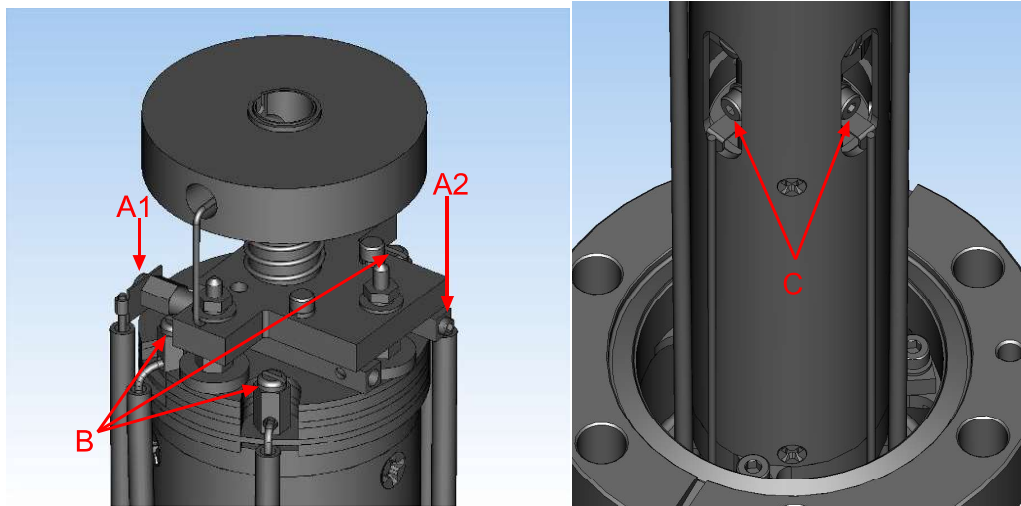
It is highly recommended to perform total pressure calibration, if possible, after replacing the ion source.

12.5.5 Electron Multiplier Replacement

The following steps should be performed to replace the electron multiplier. Use nonmetallic precision tweezers throughout replacement to aid in handling small parts.

✓ Refer to Tools Required [▶ 74] before continuing.

- 1 Remove filament lead screw (A1) using a 1.5 mm flat blade screwdriver, loosen the filament lead screw (A2) using a 0.9 mm hex driver, and loosen the three screws (B) using a 1.5 mm flat blade screwdriver. Using the 1.5 × 50 mm hex driver, unscrew the screws (C) that secure the two RF leads. Make sure to remove the lock washers as well. There are a total of seven leads that must be loosened.



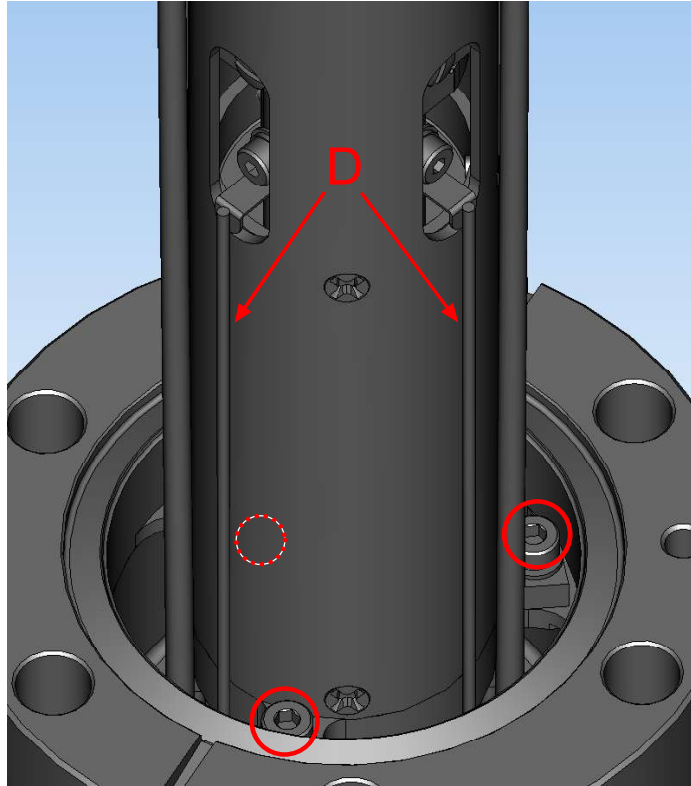
- 2 Gently pull the electrical leads away from the sensor.



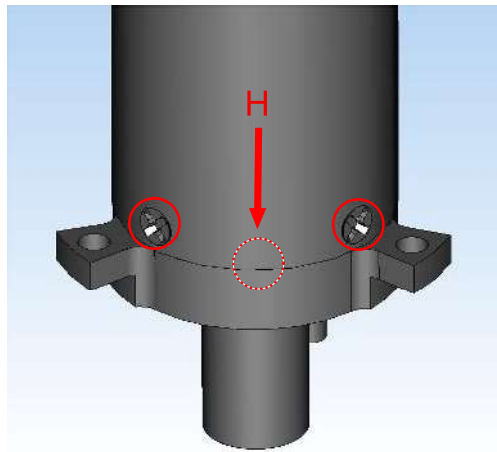
CAUTION

Do not bend the leads.

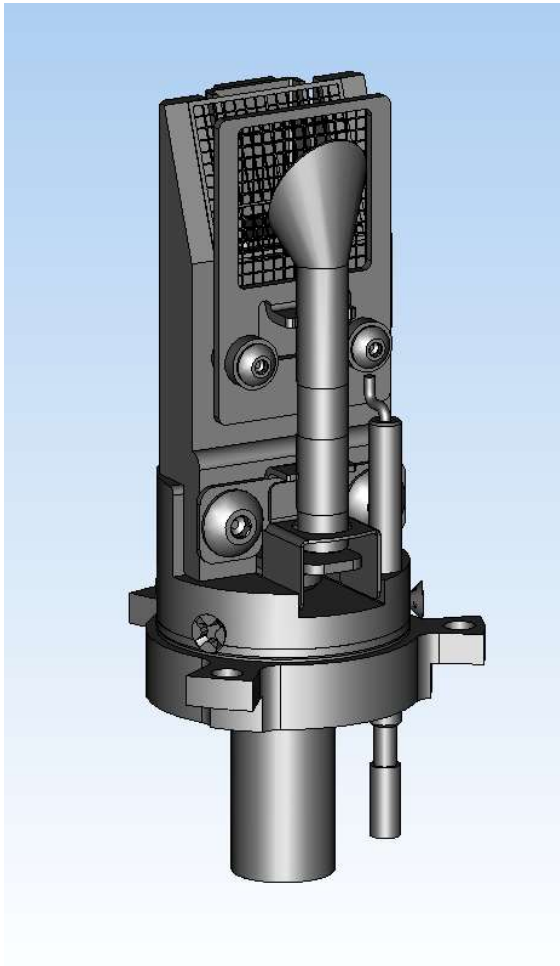
- Using the 2.0 × 75 mm hex driver, unscrew the three screws and three locking washers (circled in red, one is hidden in the figure) holding the sensor assembly to the feedthrough. Gently remove the sensor assembly from the feedthrough. It may be necessary to remove the RF leads (D) using precision pliers.



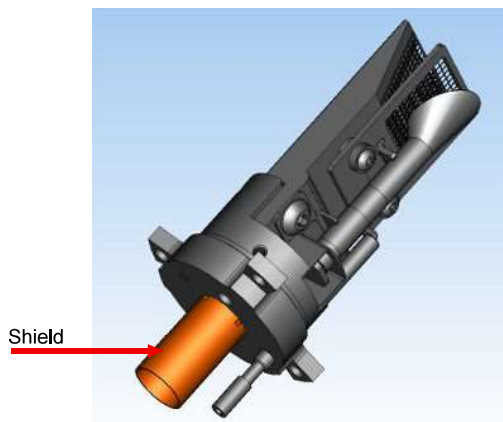
- Using a #1 Phillips head screwdriver, remove three gold screws (H, one is hidden in the figure) holding the EM assembly inside of the sensor assembly.



- Gripping the bottom of the EM assembly, gently remove the EM assembly from the sensor assembly.

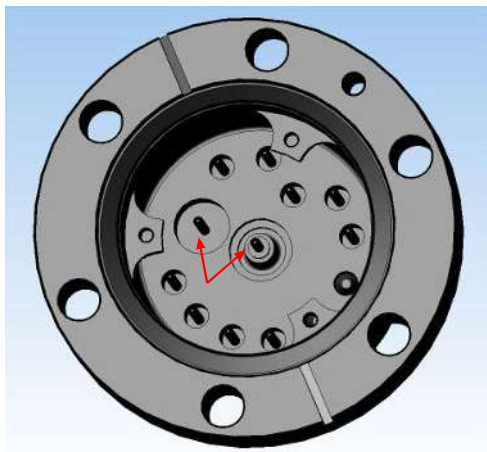


- 6 Remove the signal shield on the bottom of the old detector assembly.



- 7 Install the signal shield removed in step 6 onto the new electron multiplier assembly.
- 8 Inspect the feedthrough pins for any contacts that may have come loose from the old detector and remove the contact from the feedthrough pin prior to installing the new detector.
- 9 Install the new electron multiplier assembly into the sensor can.

- 10** When installing the sensor back into the feedthrough, ensure that the two pins on the bottom of the detector align with the two pins on the feedthrough.



- 11** Reverse steps 1–4 to reassemble the Transpector CPX sensor.



It is required to tune the mass-scale table, calibrate Faraday sensitivity, and calibrate sensitivity and EM gain before using the RGA.

12.5.6 Foreline Pump

Replacement Interval The foreline pump diaphragm disks, valve seals, valve disks, and O-rings must be replaced every 8000 hours of operation, when used in an inert environment. More frequent diaphragm replacement is required in less-than-optimal operating/process conditions.

Diaphragm Kit The components of the diaphragm kit (923-418-G2) are shown in the figure below.



12.5.6.1 Diaphragm Replacement Procedure



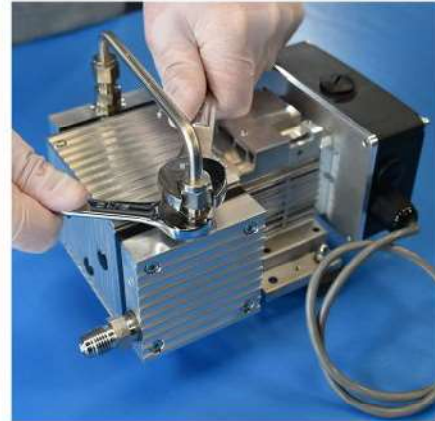
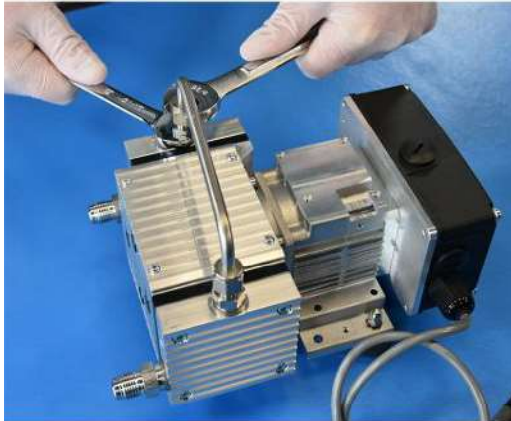
⚠ CAUTION

Wear safety glasses and protective gloves when performing this procedure.

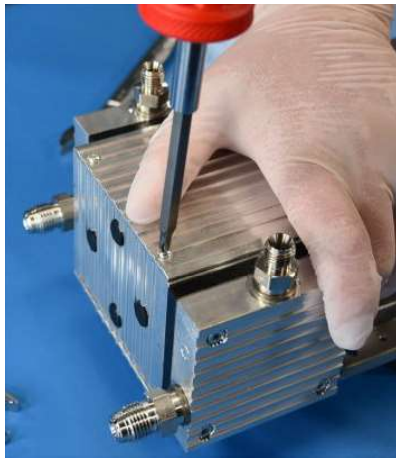
Tools Required

- Two 9/16 in. wrenches
- #1 Phillips head screwdriver
- 3 mm hex wrench
- Methanol
- Lint-free wipes

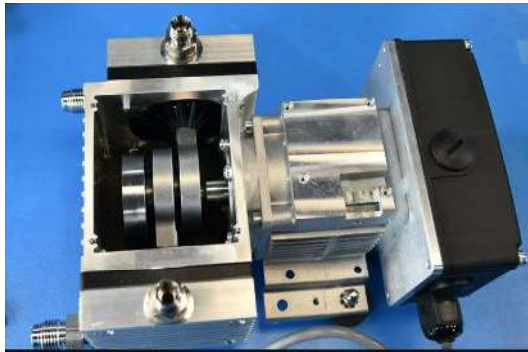
- 1** Using two 9/16 in. wrenches, remove the interstage tubing between the two pump heads.



- 2** Using a #1 Phillips head screwdriver, remove the four screws holding the cam cover on the top side of the foreline pump.



- 3** Inspect the inside of the pump for cleanliness. A buildup of a black, powdery substance indicates bearing wear and the need for pump replacement. The diaphragm disks are screwed into the cams.



- 4** Unscrew the head covers of the foreline pump using a 3 mm hex wrench.



5 Remove the foreline pump head cover and diaphragm plate.

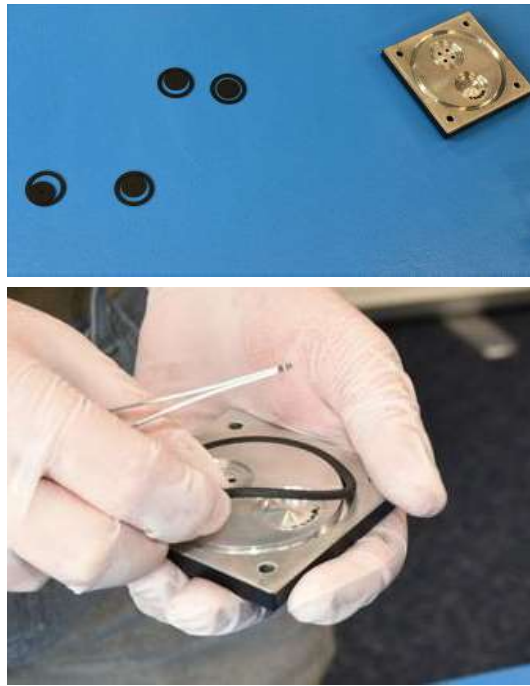


6 Separate the diaphragm plate from the head cover.



Take note of the orientation of the valves in the head cover and the diaphragm plate. They must be reassembled in exactly the same orientation.

7 Remove the old valve disks, valve seals, and O-rings from both sides of the diaphragm plate.



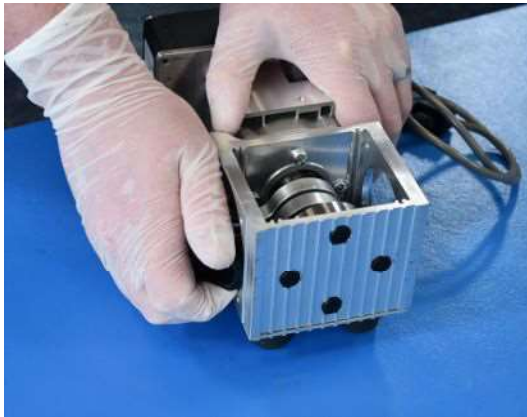
- 8 Clean both sides of the diaphragm plate and the foreline pump head cover with methanol and lint-free wipes. Pay special attention to the sealing surfaces (grooves) inside the head cover and on either side of the diaphragm plate. Make sure the diaphragm plate is in proper orientation.



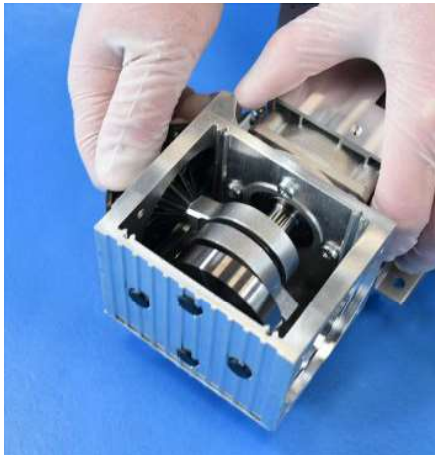
⚠ CAUTION

Read and understand the entire Methanol Material Safety Data Sheet (MSDS). Follow the precautions specified in the MSDS.

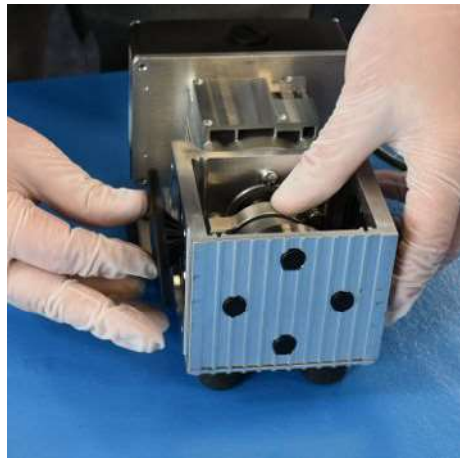
- 9 Rotate the diaphragm disk counterclockwise to unscrew the diaphragm disk from the cam. If necessary, carefully use a flathead screwdriver to pry up the diaphragm disk.



- 10** There are spacers between the diaphragm disks and the cam. Note the position of the spacers when removing the diaphragm disks. The spacers must be reassembled on the new diaphragm disks in exactly the same position.



- 11** Place the original spacers on the new replacement diaphragm in exactly the same order as they were on the old diaphragm.



The spacers cam, diaphragm disks, and electric motor are balanced at the manufacturer for optimal performance. Therefore, one side of the diaphragm may have a different number of spacers than the other in order to achieve balance. To maintain the balance, the original spacers must be transferred to the new diaphragm in exactly the same position as they were when removed from the old diaphragm.

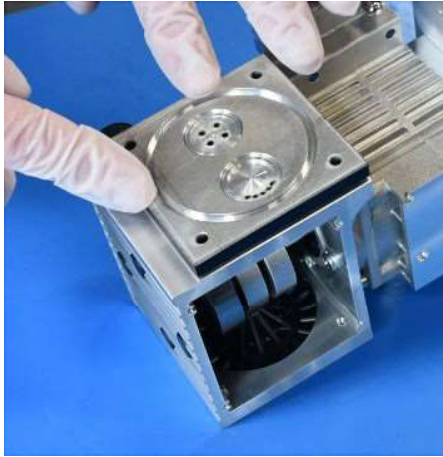
- 12 Clean the channel that the diaphragm disk is seated in with methanol and lint-free wipes. Screw the diaphragm disk, with original spacers, into the cam screw hole.



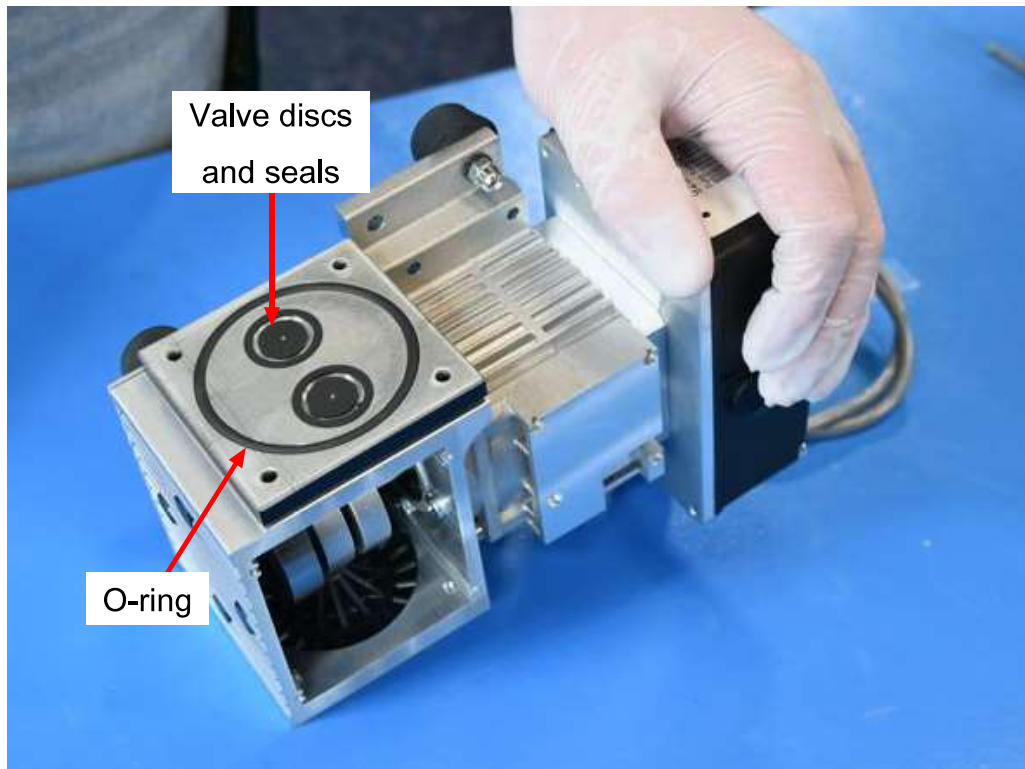
⚠ CAUTION

Screw in the diaphragm disk tightly. A loose disk can damage the pump.

- 13 Carefully place the diaphragm plate over the diaphragm head so that the screw holes line up.



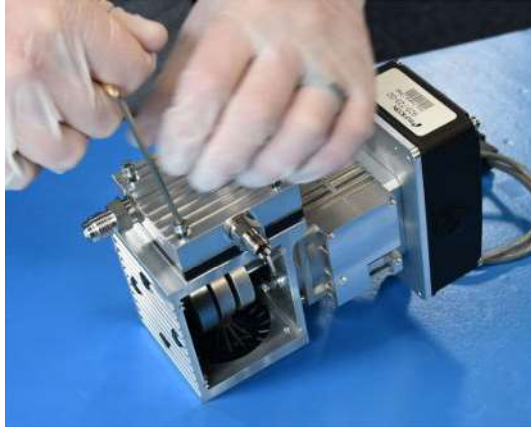
- 14** Install the new valve disks, valve seals, and the O-ring into the diaphragm plate.



- 15** Install the head cover on the diaphragm plate.



- 16** Replace the four hex screws to secure the head cover. Perform the steps again for the second pump head. Replace the cam cover and interstage tubing.



13 Service and Technical Support

13.1 How to Contact Customer Support

Worldwide customer support information is available under **Contact >> Support**

Worldwide at www.inficon.com:

- Sales and Customer Service
- Technical Support
- Repair Service

If you are experiencing a problem with Transpector CPX, please have the following information readily available:

- the Transpector CPX serial numbers
 - The sensor serial number (noted as SN) can be located on the feedthrough where the sensor connects to the electronics box. The electronics box serial number can be found on the side of the box where the sensor connects in. Both of these numbers are important to share when contacting INFICON.
- a description of the problem
- an explanation of any corrective action already attempted
- the exact wording of any error messages

13.2 Returning Your Instrument to INFICON

Do not return any component of your instrument to INFICON without first obtaining a Return Material Authorization (RMA) number from a Customer Support Representative.

If you deliver a package to INFICON without an RMA number, your package will be held and you will be contacted. This will result in delays in servicing your instrument.

Prior to being given an RMA number, you may be required to complete a Declaration of Contamination (DOC) form if your instrument has been exposed to certain materials. DOC forms must be approved by INFICON before an RMA number is issued. INFICON may require that the instrument be sent to a designated decontamination facility, not to the factory.

14 Recommended Parts List

14.1 Ordering Information

To contact INFICON order services regarding Transpector CPX, please use the following contact information:

INFICON, Inc.
 Two Technology Place
 East Syracuse, NY 13057
 USA
 Tel: +315.434.1100
 Email: reachus@inficon.com

14.2 Sensors

The following spare parts should be readily available.

Part Number	Description
961-M1MCS	100 AMU sensor - coated single filament
961-M2MCS	200 AMU sensor - coated single filament
961-M3MCS	300 AMU sensor - coated single filament
961-M1MHS	100 AMU sensor - coated single filament + anode liner
961-M2MHS	200 AMU sensor - coated single filament + anode liner
961-M3MHS	300 AMU sensor - coated single filament + anode liner
961-M1MDS	100 AMU sensor - tungsten single filament
961-M2MDS	200 AMU sensor - tungsten single filament
961-M3MDS	300 AMU sensor - tungsten single filament
961-M1MJS	100 AMU sensor - tungsten single filament + anode liner
961-M2MJS	200 AMU sensor - tungsten single filament + anode liner
961-M3MJS	300 AMU sensor - tungsten single filament + anode liner

14.3 Consumable Parts

The following spare parts should be readily available.

Part Number	Description
969-818-G2S	SF-CIS coated filament kit
969-818-G1S	SF-CIS tungsten filament kit

Part Number	Description
969-819-G3S	SF-CIS coated ion source kit
969-819-G1S	SF-CIS tungsten ion source kit
969-819-G2S	SF-CIS tungsten ion source kit + anode liner
915-724-G1	Spare anode liner [qty. 3]
961-707-G1	Electron multiplier replacement kit
961-2333-G6S	Filament and anode lead assy w/ ceramic tube kit [qty. 3]
961-2333-G7S	Total pressure lead assy w/ ceramic tube kit
961-2335-G1S	EM lead assy w/ ceramic tube kit
961-2334-G1S	EM RF lead assy w/ ceramic tube kit [qty. 2]
961-3000-G1S	MMSP 11 pin feedthrough assy kit
019-130-P1S	Spacer kit [qty. 15]
908-067-P1S	D-seal kit [qty. 1]
915-376-P1S	Retainer clip kit [qty. 6]
915-375-P1S	Seal disk spring kit [qty. 1]
915-379-P1S	Stud #0-80 kit [qty. 6]
908-055-P1S	CIS insulator ring kit [qty. 3]
908-060-P1S	Ceramic washer kit [qty. 15]
908-601-P1S	Shield washer kit [qty. 9]
915-385-P2S	Threaded standoff kit [qty. 120]
080-007-P1S	Flat SS washer kit [qty. 120]
080-012-P3S	Slot pan screw kit [qty. 120]
080-024S	Split lock SS washer 0 × 0.100 OD kit [qty. 120]
080-021S	LG SOC HD cap screw 0-80 × 0.250 kit [qty. 120]

14.4 Electronic Boxes

The following spare parts should be readily available.

Part Number	Description
AP-M110S	CPX 100 AMU electronics box
AP-M210S	CPX 200 AMU electronics box
AP-M310S	CPX 300 AMU electronics box

14.5 Pumps and Maintenance Kits

The following spare parts should be readily available.

Part Number	Description
969-270-G1S	2-stage diaphragm pump - no cable
923-418-G2	Replacement diaphragm kit for 2-stage pump
969-802-G1S	Pump and manifold - noncorrosive system
969-804-G1S	Pump and manifold - corrosive system

14.6 CDGs

The following spare parts should be readily available.

Part Number	Description
969-806-G1S	1 Torr male gauge
969-807-G1S	10 Torr male gauge
969-808-G1S	100 Torr male gauge
969-809-G1S	1000 Torr male gauge

14.7 Inlet Assembly and Parts

The following spare parts should be readily available.

Part Number	Description
059-0391S	Silver-plated male VCR nut (SS-4-VCR-4-SP)
923-310-P2S	Blank polished HexBlock
923-700-G1S	KF25 in-line connection
923-701-G1S	KF40 in-line connection
923-702-G1S	CF40 in-line connection
923-703-G1S	KF25 elbow connection
923-704-G1S	KF40 elbow connection
923-705-G1S	CF40 elbow connection
969-724-G1S	KF25 to VCR kit [qty. 4]
969-810-G1S	Packaging kit
969-827-G1S	Pressure switch kit
969-605-G1S	Platform bypass kit
969-812-G1S	N2 purge kit
969-813-G1S	Spare pumping system fan kit

14.8 Atmospheric Inlet Accessories

The following spare parts should be readily available.

Part Number	Description
922-204-G1	Capillary assembly, 1.5 m
922-204-G3	Capillary assembly, 3 m

14.9 Orifice Kits

The following spare parts should be readily available.

Part Number	Description
923-706-G6S	10 mTorr HexBlock orifice (750 μm)
923-706-G11S	15 mTorr HexBlock orifice (350 μm)
923-706-G8S	15 mTorr bypass orifice (350 μm)
923-706-G5S	100 mTorr HexBlock orifice (200 μm)
923-706-G7S	360 mTorr HexBlock orifice (95 μm)
923-706-G4S	1 Torr HexBlock orifice (62 μm)
923-706-G9S	3 Torr HexBlock orifice (35 μm)
923-706-G3S	10 Torr HexBlock orifice (20 μm)
923-706-G10S	30 Torr HexBlock orifice (10.5 μm)
923-707-G3S	7 Torr HexBlock sniffer (5 cm length)
923-707-G1S	10 Torr HexBlock sniffer (5 cm length)
923-707-G7S	10 Torr HexBlock sniffer (30.5 cm length)
923-707-G4S	30 Torr HexBlock sniffer (10 cm length)
923-707-G6S	30 Torr HexBlock sniffer (30.5 cm length)
923-707-G2S	100 Torr HexBlock sniffer (5 cm length)
923-707-G5S	300 Torr HexBlock sniffer (5 cm length)
059-0400	Replacement C-ring

14.10 Pumping System Hardware

The following spare parts should be readily available.

Part Number	Description
059-0828S	Retained nickel gasket
059-0826S	Unretained nickel gasket
059-0287S	KQ2H07-32,10-32 to 1/4 in. quick connect kit [qty. 100]

Part Number	Description
059-0293S	Slotted hex head plug, M5 SS threaded kit [qty. 100]
059-0346S	KQ2U07-00, Y union, 1/4-tube, push-in kit [qty. 100]
059-0368S	Viton gasket fitting kit [qty. 5]
059-0407S	Male elbow, 1/8-tube, 10-32 kit [qty. 60]
059-0408S	Male elbow, 1/4-tube, 10-32 kit [qty. 60]
969-3017-P1S	G-1/4 sealing ring
059-0418S	VCR adapter, male to 1/8 ISO (SS-4-VCR-1-R2S) kit [qty. 4]
059-0605S	1/16-tube, 1/8-ISO-M parallel SS connector kit [qty. 30]
059-0827S	1/4-in. VCR to 1/4-in. RS
096-030S	Plain SS 0.25 washer kit [qty. 1000]
096-038S	0.25-28 × 0.875 LG SS SP 12PT HD bolt kit [qty. 180]
144-078S	M4-0.7 × 8 mm LG SOC SS HD cap screw kit [qty. 100]
144-080S	M4.7 × 25 mm LG PH PAN SS HD screw kit [qty. 100]
144-278S	M3 × 8 LG SPC FL HD screw kit [qty. 50]
144-280S	M3 × 25 LF SOC FL HD screw kit [qty. 50]
144-353S	M3 × 30 mm socket head cap screw kit [qty. 100]
969-815-G1S	Pressure switch bracket
969-816-G1S	Purge tube kit
969-817-G1S	Foreline tube kit
923-713-G2	Calibration reference
969-713-G1S	Platform calibration reference bracket w/ tubing + gasket
070-0863S	Nut plate kit [qty. 30]
070-1057S	5 mm THD knurled bronze silencer kit [qty. 30]
070-1136S	8 mm M6 thread T-nut kit [qty. 24]
070-1654S	Viton O-ring kit [qty. 50]
964-082-G1S	HexBlock valve plug kit

14.11 Heaters/Insulators

The following spare parts should be readily available.

Part Number	Description
969-719-G1S	Manifold heater cover kit
969-722-G1S	HexBlock heater cover without QCM kit
600-1596-P4S	Heater/RTD cable - manifold

14.12 Cables and Hoses

The following spare parts should be readily available.

Part Number	Description
600-1621-P1S	Power supply
969-329-P1S	24 V (DC) 2 m power supply
600-1597-P1S	Turbo cable
600-1598-P1S	Foreline gauge cable
600-1599-P1S	Valve manifold cable
600-1600-P1S	CDG cable
600-1600-P2S	30 in. CDG cable
600-1601-P1S	Porter® cable
600-1622-P1S	Power extension cable (pigtail)
969-021-G1S	Standard US plug
969-021-G2S	3 m US plug
969-021-G3S	5 m US plug
969-021-G4S	Standard EUR plug
959-021-G5S	3 m EUR plug
969-021-G6S	5 m EUR plug
969-021-G7S	Standard IL plug
969-021-G8S	3 m IL plug
969-021-G9S	5 m IL Plug
969-021-G10S	Standard UK plug
969-021-G11S	3 m UK plug
969-021-G12S	5 m UK plug
600-1605-P1S	1 m foreline pump cable
600-1605-P3S	3 m foreline pump cable
600-1605-P5S	5 m foreline pump cable
600-1605-P10S	10 m foreline pump cable
922-205-G1S	1 m foreline hose
922-205-G3S	3 m foreline hose
922-205-G5S	5 m foreline hose
922-205-G10S	10 m foreline hose

14.13 Preventative Maintenance Kits

The following spare parts should be readily available.

Part Number	Description
923-712-G1	HexBlock orifice gasket [qty. 5]
923-711-G1	HexBlock valve replacement kit
969-840-G1S	HexBlock valve replacement + Kalrez® O-ring kit
923-710-G1	HexBlock orifice replacement tools

14.14 Other Accessories

The following spare parts should be readily available.

Part Number	Description
923-417-1	Foreline check valve for overpressure protection kit
969-257-G1S	Pneumatic assembly

15 Glossary

Anode	The anode is the structure in the ion source in which ions are created by electron impact. It can be formed from a mesh, such as in the open ion source, or from a solid tube, such as in the closed ion source. Its electrical potential is positive with respect to the filament, focus lens, total pressure plate, pole zero, exit aperture, and Faraday cup.
Appearance potential	The minimum electron energy required to produce, by electron bombardment, a given ion in its lowest energy state.
Atomic mass unit (AMU)	An atomic mass unit is a unit of measurement for the mass of a molecule or ion. It is based on the definition that the mass of an atom of the carbon-12 isotope is exactly 12.
Background	The background is the residual atmosphere in a vacuum apparatus when no gases are being deliberately introduced.
Bakeout	Bakeout is the process of heating a vacuum chamber above the ambient temperature in order to accelerate the desorption of species such as water vapor and hydrocarbons which are adsorbed onto the inner surfaces of the vacuum chamber.
Center voltage	The center voltage is the DC potential to which the quadrupole rod RF and differential DC potentials are referenced.
Closed ion source (CIS)	The closed ion source is an ion source in which the pressure in the ionization region is higher than in the rest of the analyzer sensor. This is usually accomplished by fabricating the anode from a solid walled tube instead of an open mesh. This type of source is usually employed to measure trace contaminant levels in a process gas.
Conductance	The conductance of a gas flow channel is the ratio of the gas quantity flowing through the channel to the pressure drop across that channel.
Cracking pattern	See Fragmentation pattern .
Detection factor	The detection factor is the ratio of the detected signal for a given ion current from a certain substance to the detected signal for the same ion current of nitrogen ions as measured at mass 28. For Faraday cup detectors, the detection factor is usually 1. For electron multiplier detectors, this factor depends on the mass and chemical nature of the ion.
Detector	The detector is that part of the mass spectrometer sensor which converts a beam of ions into an electrical signal.
Doubly charged ion	For positive ions, a doubly charged ion is a parent or fragment ion where two electrons have been removed.
Electron energy	The electron energy is the kinetic energy of the ionizing electrons in an electron bombardment ion source and is typically measured in units of electron volts (eV). The electron energy is approximately equal to the difference between the bias voltage on the filament and the anode potential, times the electron charge.

Electron multiplier	An electron multiplier is an in situ amplifier which is used to increase the sensitivity of a mass spectrometer. When a high voltage is applied to an electron multiplier, positive ions are accelerated into the multiplier, causing the release of a large number of electrons per incident ion at the output.
Emission current	The emission current is the current of electrons leaving the surface of a heated filament.
Exit aperture (quadrupole)	The exit aperture is a focus lens at the ion exit (detector) end of a quadrupole mass spectrometer. This lens is often biased by a potential that is negative with respect to the quadrupole center voltage such that ions are extracted from the exit end of the quadrupole and focused into the detector.
Extractor	See Focus lens .
Faraday cup	The Faraday Cup is a detector for ions and/or electrons consisting of a cup-shaped, conductive electrode.
Filament	The filament is a fine wire or ribbon, which, when heated by means of electrical current, emits electrons. The filament typically made of iridium with a thorium or yttrium oxide coating, or of tungsten or a tungsten alloy.
Focus lens	The focus lens is a conductive aperture located next to, and usually biased negatively with respect to, the anode. Its purpose is to draw the ions out of the anode, form them into a beam, and focus them into the next lens element.
Fragment ion	A fragment ion is an ion with fewer atoms than the parent gas molecule from which the ion is produced. The mass of the fragment ion is always less than that of the parent ion.
Fragmentation factor	The fragmentation factor is the fraction of the total ions produced from a specified substance which have a given mass. The sum of the fragmentation factors for all of the ions produced from a specified substance is equal to one.
Fragmentation pattern	The fragmentation pattern is the pattern of ion masses and intensities produced by electron bombardment of a specified gas species as transmitted by the mass filter, detected, and recorded.
Gain (electron multiplier)	The gain of an electron multiplier is the ratio of incident ion current to electron current output. The gain of the multiplier is a strong function of the bias potential applied across it.
Ion	An ion is a molecule or atom which has either lost or added one or more electrons. Those molecules which have lost electrons are positive ions. Those molecules which have added electrons are negative ions.
Ion current	An ion current is the rate of flow of electrical charge associated with the flow of ions.

Ion energy	The ion energy is the kinetic energy associated with a beam of ions. It is equal to the potential difference across which the ion beam is accelerated (or decelerated) times the charge on the ion and is typically measured in electron volts (eV). Specifically, in a quadrupole mass spectrometer, it is the kinetic energy, along the axis, of the ions as they pass through the mass filter. The ion energy is approximately equal to the anode potential minus the quadrupole center voltage time the ionic charge.
Ion source	The ion source is that part of a mass spectrometer in which neutral gas molecules or atoms are ionized by electron bombardment.
Ionization probability	The ionization probability for a chemical substance is the ratio of the total ion current (at all masses) produced from a given partial pressure of that substance, to the total ion current produced from nitrogen at the same partial pressure.
Isotope	The atom is composed of nucleus protons and neutrons surrounded by an electron cloud. The chemical properties of an element are determined by the number and arrangement of electrons (with -1 charge) in an atom. The number of electrons in a neutral atom in turn depends on the number of protons (with +1 charge) within the nucleus of that atom. Atomic nuclei also contain neutrons which, being uncharged, do not affect the chemistry of an element. Protons and neutrons have approximately the same mass, which is approximately 1800 times the mass of an electron. All atoms of a given element have the same number of protons but not necessarily the same number of neutrons. Atoms of the same element which have a different number of neutrons are called isotopes. See also Natural abundance .
Linearity	Linearity is the mathematical relationship between an ion current and the total or partial pressure giving rise to that current. A mass spectrometer is said to have good linearity when the ion current is proportional to the pressure over a specified pressure range within a specified tolerance. Typically (but not always), the ion current will be linear with pressure at the low end of an instrument's pressure range. At some pressure near the high pressure end of an instrument's range, the ion current will be less than proportional to the pressure.
Mass-to-charge ratio	The mass-to-charge ratio is ratio of the mass of an ion to its charge, usually expressed in atomic mass units per unit electron charge.
Mass filter	The mass filter is that part of the mass spectrometer which separates a beam of ions by their mass to charge ratios.
Mass spectrometer	A mass spectrometer is an instrument which ionizes a gas sample, separates the resulting beam of ions by mass to charge ratio, and detects the filtered ions as an electrical signal.
Mass spectrum	A mass spectrum is a record of ion current as a function of mass to charge ratio obtained with a mass spectrometer. The spectrum can be presented as a graph with mass to charge ratio on the x axis and ion current on the y axis, or as a tabular listing of ion currents and the associated mass to charge ratios.

Material factor	The material factor for a chemical substance is that part of the proportionality constant between the partial pressure of that substance and the resulting mass filtered ion current which depends on the chemical nature of that substance but not the particular instrument used for that measurement. The material factor is a function of the ionization probability and fragmentation factor for the specified substance.
Mean free path	The mean free path is the average distance an ion, electron, atom, or molecule can travel before colliding with an ambient gas molecule. The mean free path is inversely proportional to the pressure.
Molecular flow	Molecular flow is that motion of gas molecules wherein the collisional mean free path is greater than the critical dimension of a flow constraining element such as an orifice of tube diameter. The gas flow characteristics are dominated by collisions between the gas molecules and the appropriate surfaces of the vacuum system.
Natural abundance	<p>The natural abundance of an isotope is the average percentage of all atoms of a given element which have the same number of neutrons. For example, 99.985% of all naturally occurring hydrogen atoms have no neutrons, giving an atomic mass of approximately 1, while 0.015% have one neutron, giving an atomic mass of approximately 2. There is a third isotope of hydrogen which contains two neutrons, giving an atomic mass of 3, but this isotope is unstable with such a short radioactive half life that it is not normally naturally occurring in any significant quantity on earth.</p> <p>There are occasions when an observed isotopic abundance will not reflect the natural abundance. For instance, in semiconductor processing tools known as ion implanters, it is not unusual for the BF₃ boron dopant source to be isotopically enriched to 99%+ of the boron-11 isotope (instead of the naturally occurring 80.22%).</p>
Open ion source (OIS)	An open ion source is an ion source constructed with an open grid structure with high conductance between the ionization region and the vacuum region surrounding it. Residual gas analyzers are typically equipped with this type of ion source.
Outgassing	Outgassing is the evolution of gas which was dissolved in or adsorbed on solid surfaces inside a vacuum chamber.
Parent ion	A parent ion is an ion made by removing a single electron from the original, or parent, gas molecule, and therefore has the same mass.
Partial pressure	The partial pressure is the pressure of a specific chemical component of a gas mixture. The sum of all the partial pressures is the total pressure.
Pole zero	See Center voltage .
Quadrupole	A quadrupole is a mass filter consisting of four parallel electrodes or poles (hence quadrupole) arranged in a square array. Opposite poles are connected together electrically such that an electric field of hyperbolic geometry is produced. The potentials applied to these poles are a superposition of variable DC and RF voltages, generally of fixed RF frequency.
Repeller (electron)	The electron repeller is an electrode located on the opposite side of the filament than the anode. The repeller is usually biased at the same potential as the negative side of the filament or at a more negative potential.

Residual gas analyzer	A residual gas analyzer is an instrument which is used to determine the quantities and chemical nature of gases present in a vacuum system. The instrument is typically a mass spectrometer equipped with an open ion source.
Resolution	Resolution is the ability of a mass filter to select between nearby masses. It is typically measured as the mass of the peak divided by the width of a given mass peak at 10% or 50% of the peak maximum intensity.
Secondary electron	A secondary electron is an electron emitted from a surface when that surface is struck by a sufficiently energetic ion, electron, neutral molecule, or photon.
Sensitivity	The sensitivity of a mass spectrometer is the ratio of ion current at a specified mass from a specified gas to the partial pressure of that gas, suitably corrected for background. The specified gas is typically nitrogen, measured at 28 AMU, although argon at 40 AMU is sometimes used instead, depending on the instrument.
Total pressure	The total pressure is the force per unit area exerted by a gas on the walls of its container. It is equal to the sum of all the partial pressures of the different chemical species which comprise that gas.
Total pressure plate	The total pressure plate, or collector, is an electrode in the ion source on which at least a part of the ion beam impinges. The current striking this plate is a function of the total pressure in the ion source.
Transition flow	Transition flow is that motion of gas molecules wherein the collisional mean free path is approximately the same as the critical dimension of a flow constraining element such as an orifice of tube diameter.
Transmission factor	The transmission factor is the ratio of ion current detected at the exit end of the mass filter (set to transmit a given mass) to the current of ions of the same mass entering the filter from the ion source. Typically, the transmission factor for nitrogen ions at 28 AMU is set equal to 1. The transmission factor at other masses is given relative to that for nitrogen.
Viscous flow	Viscous flow is that motion of gas molecules wherein the collisional mean free path is less than the critical dimension of a flow constraining element such as an orifice of tube diameter. The gas flow characteristics are dominated by collisions between gas molecules.
Zero blast	Zero blast is the ion current which is not mass filtered and is detected when the mass spectrometer is scanning near mass zero.

16 Declaration of Conformity



**DECLARATION
OF
CONFORMITY**

This declaration is issued under the sole responsibility of the manufacturer INFICON. The object of the declaration is to certify that this equipment, designed and manufactured by:

**INFICON Inc.
Two Technology Place
East Syracuse, NY 13057
USA**

is in conformity with the relevant Community harmonization legislation. It has been constructed in accordance with good engineering practice in safety matters in force in the Community and does not endanger the safety of persons, domestic animals or property when properly installed and maintained and used in applications for which it was made.

Equipment Description: INFICON Transpector APXA, APXH, CPXH, SPXP Residual Gas Analyzer

Applicable Directives:

2014/35/EU (LVD)	Electrical Equipment (Safety) Regulations 2018 (UK)
2014/30/EU (EMC)	Electromagnetic Compatibility Regulations 2016 (UK)
2015/863/EU (RoHS)	Substances in Electrical and Electronic Equipment Regulations 2012 (AS AMENDED)

Applicable Standards:

Safety: IEC 61010-1:2010/AMD1:2016 3rd Edition: Listing # E115486

Emissions: EN 61326-1:2020 (Radiated & Conducted Emissions)
(EMC – Measurement, Control & Laboratory Equipment)

CISPR 11:2015/AMD2:2019
EN 55011:2016/A11:2020 Emission Standard for Industrial, Scientific and Medical (ISM) radio RF equipment
FCC Title 47 CFR Part 18 Class A emission requirements (USA)

Immunity: EN 61326:2020 (Industrial EMC Environments)
(EMC – Measurement, Control & Laboratory Equipment)
Immunity per Table 2

SEMI: SEMI S2-0821 Compliant

CE and UKCA Implementation Date: October 18, 2022

Authorized Representatives:

<p>Andrew Klamm <small>Digitally signed by Andrew Klamm Date: 2022.11.03 18:07:30 +0500</small></p> <hr/> <p>Andrew Klamm Quality Manager, ISS</p>	<p>Samuel Carroll <small>Digitally signed by Samuel Carroll Date: 2022.10.24 14:34:01 +0500</small></p> <hr/> <p>Samuel Carroll Vice President of Engineering</p>
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ANY QUESTIONS RELATIVE TO THIS DECLARATION OR TO THE SAFETY OF INFICON'S PRODUCTS SHOULD BE DIRECTED, IN WRITING, TO THE AUTHORIZED REPRESENTATIVE AT THE ABOVE ADDRESS.



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